

RD50 CMOS

Eva Vilella

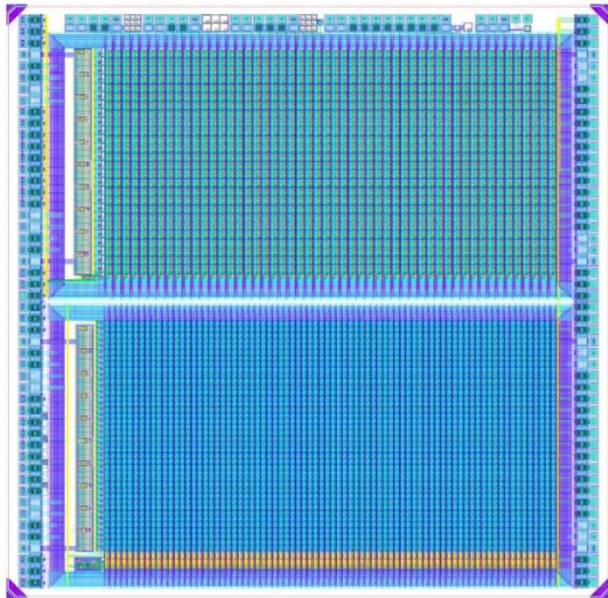
On behalf of many people... (see slides)

University of Liverpool

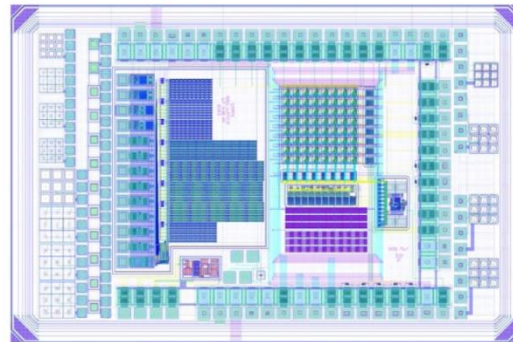
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RD50-MPWx chip series

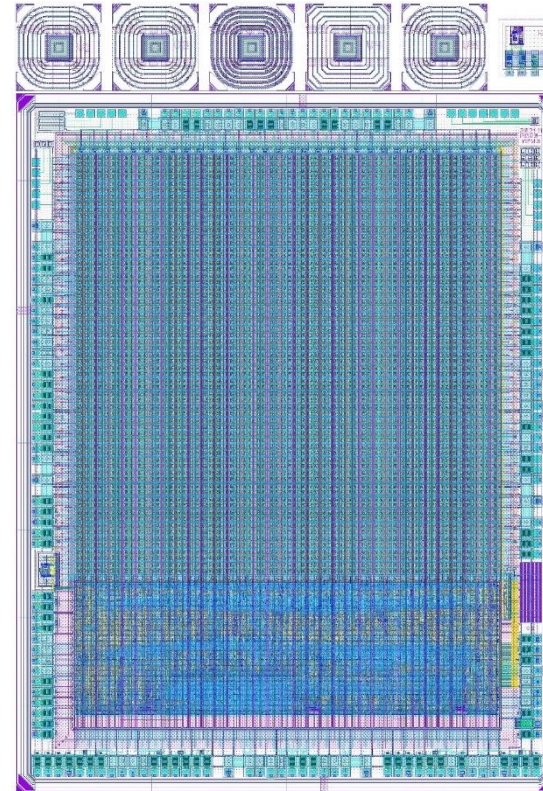
RD50-MPW1



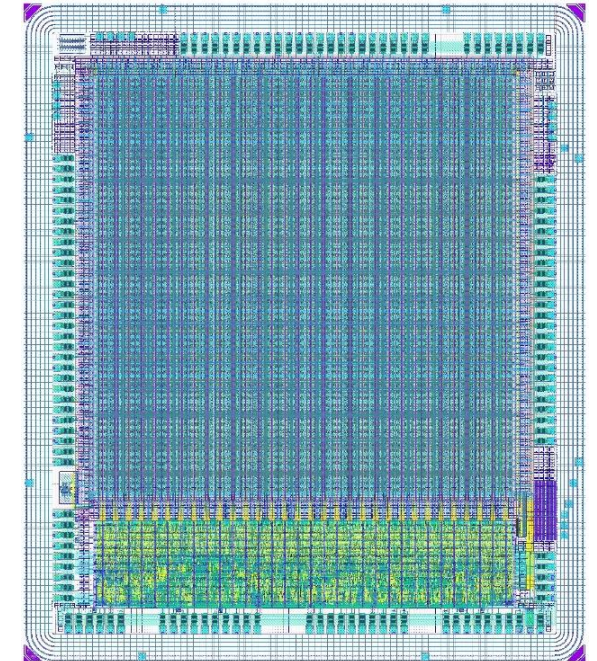
RD50-MPW2



RD50-MPW3



RD50-MPW4



The institutes



The people

Thomas Bergauer
Sebastian Grinstein
Ivan Vila
Marlon Barbero
Nicola Massari
Christian Irmeler
Raimon Casanova
Ricardo Marco
Patrick Pangaud
Patrick Sieberer
Jose Mazorra de Cos
Gregor Kramberger
Helmut Steininger
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Oscar Alonso
José María Hinojo
Eva Vilella
Gianluigi Casse
Matt Franks
Ben Wade
Hans Krueger
Jan Hammerich
Nissar Karim

Apologies if I have missed your name... in that case let me know and I will add it

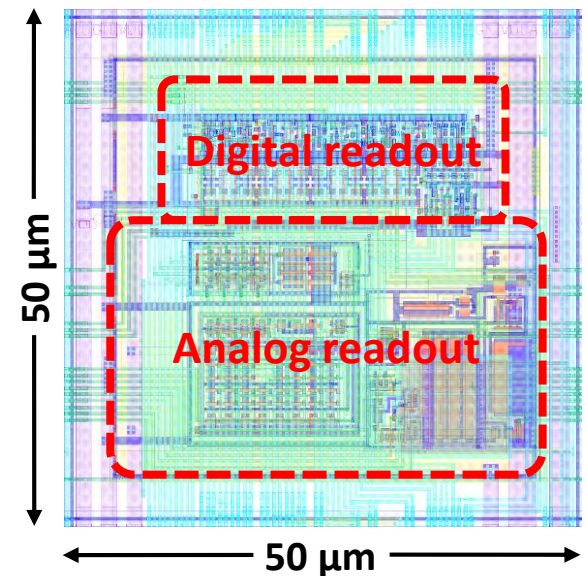
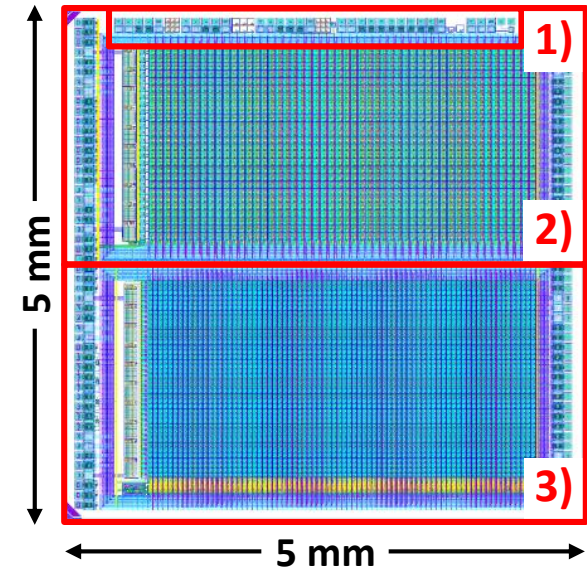
RD50-MPW1 (common project 2017-07)

▪ Main goals

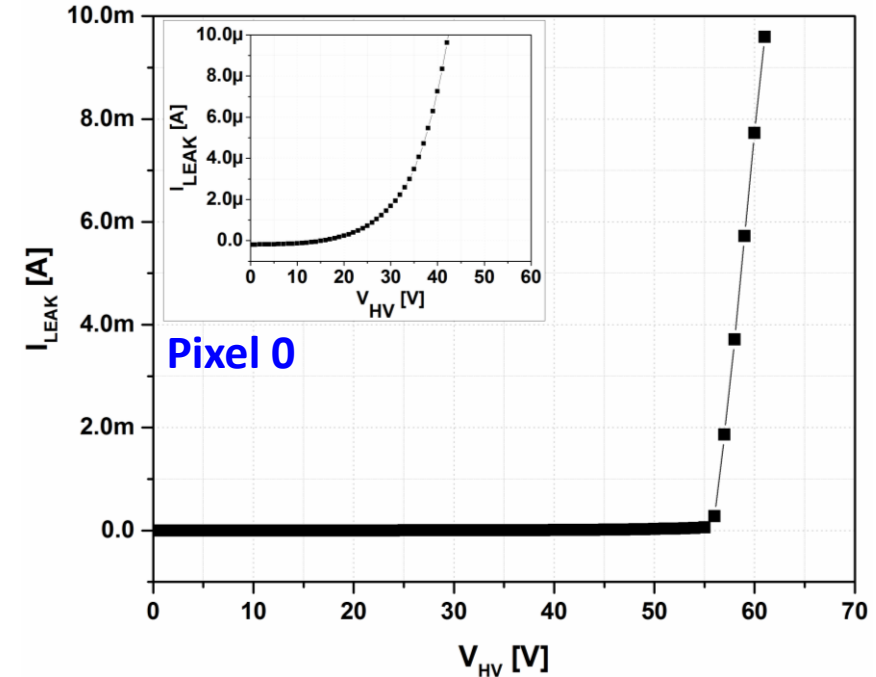
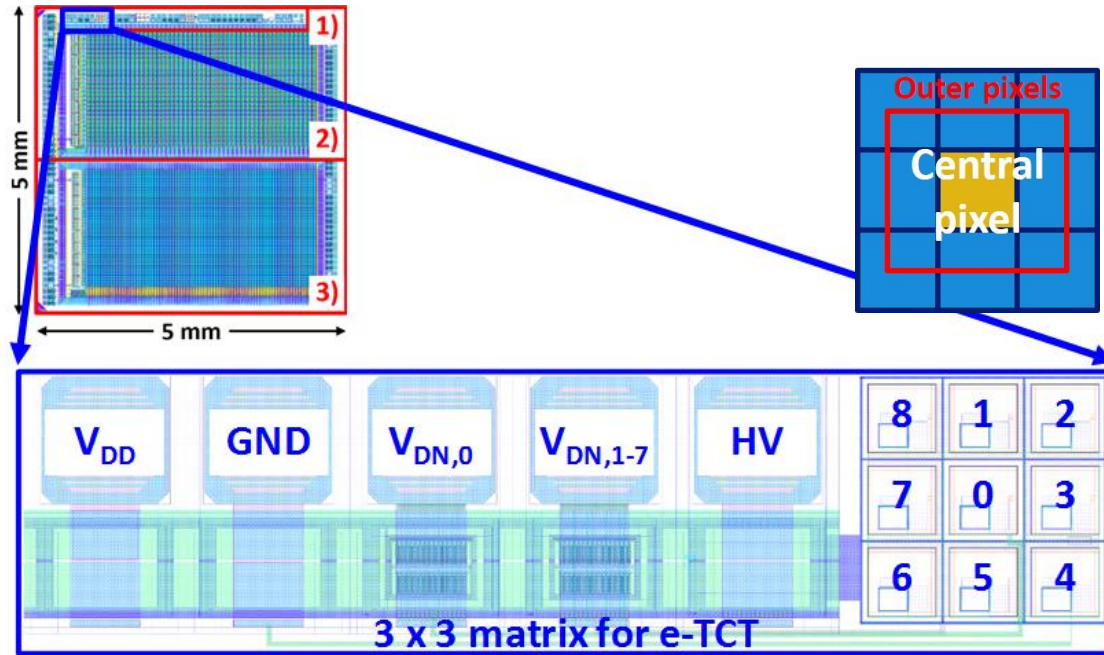
- To gain expertise, test the process (LFoundry 150 nm HV-CMOS) and test novel designs
- Process regarded attractive because of HV, nested wells, access to HR wafers in MPW submissions and affordable cost

▪ Chip contents

- Tests structures for e-TCT and C_{DET} measurements
- Matrix of depleted CMOS pixels with 16-bit counters
 - 26 x 52 pixels
 - 75 μm x 75 μm pixel area
- Matrix of depleted CMOS pixels with FE-I3 style readout
 - 40 x 78 pixels
 - 50 μm x 50 μm pixel area
- Analog and digital readout embedded in the sensing area
- One LVDS link per matrix
- Fabricated on 500 $\Omega\cdot\text{cm}$ and 1.9k $\Omega\cdot\text{cm}$ wafers



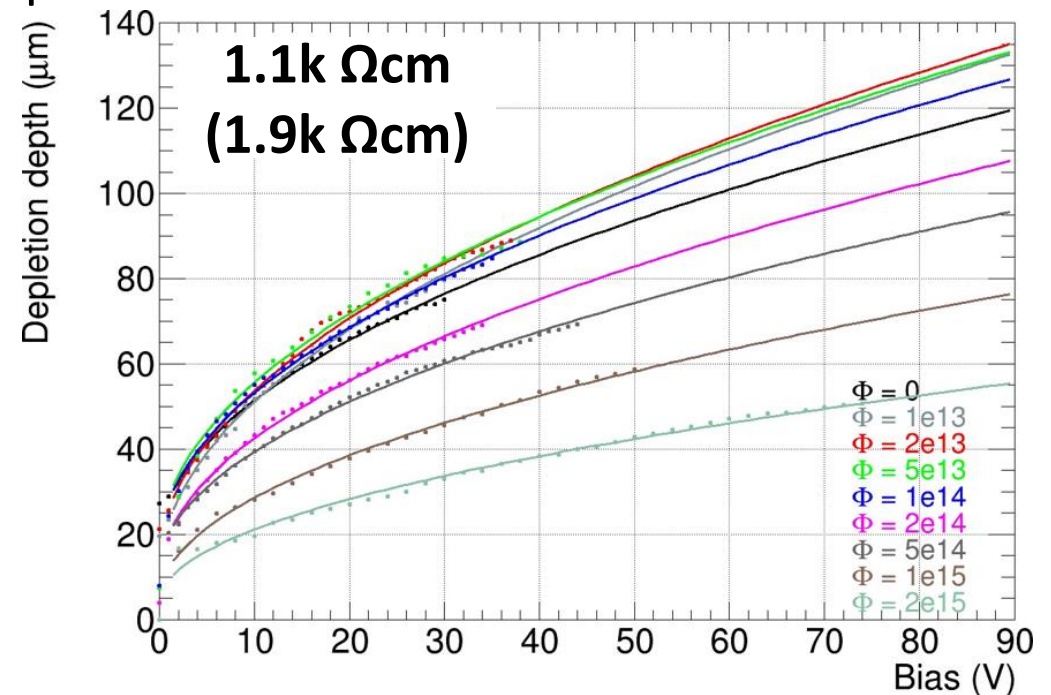
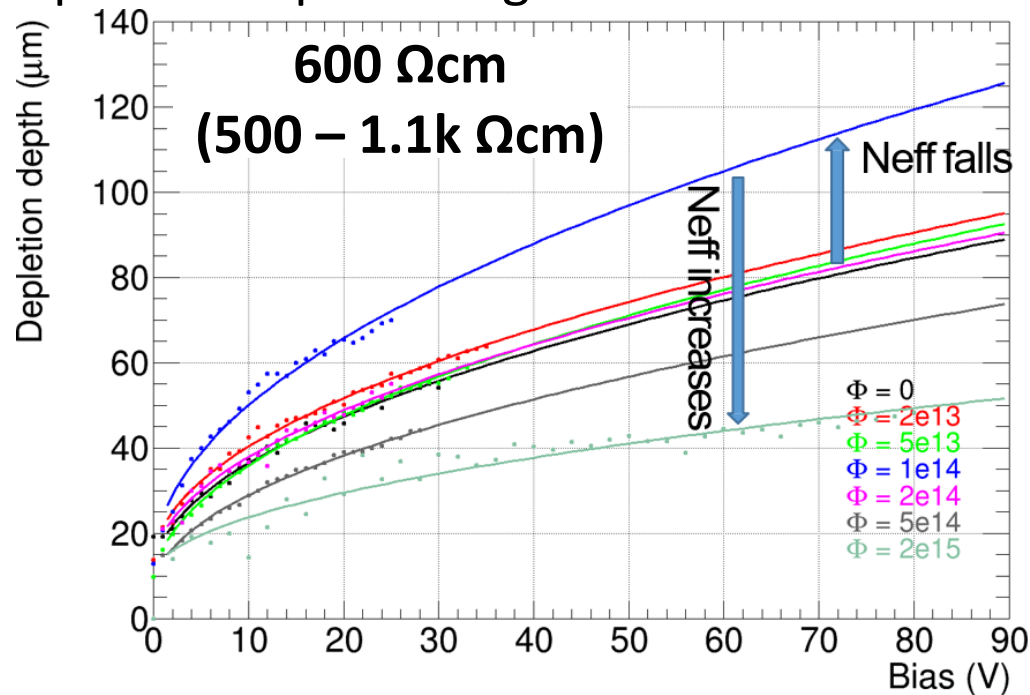
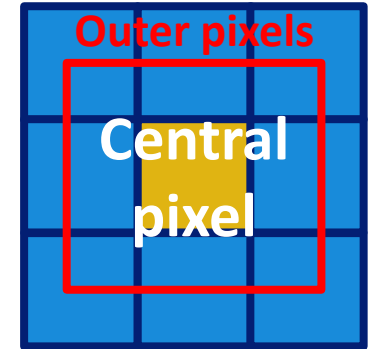
RD50-MPW1 – Current-to-voltage characteristics



- I-V of central pixel (50 μ m x 50 μ m)
- Measurement done using a probe station with sensor in complete darkness
- $V_{BD} \sim 55-60$ V as expected from design, but I_{LEAK} was too high
- Despite high I_{LEAK} , the chip worked
- The issue was extensively studied: TCAD simulations + support from the foundry (we learned a lot)

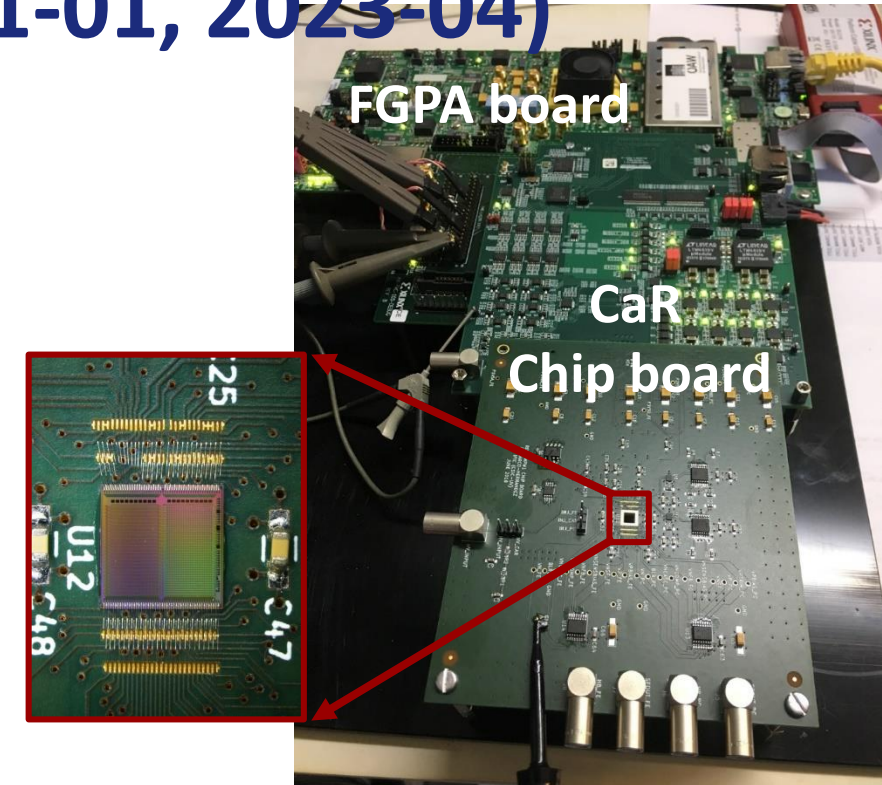
RD50-MPW1 – eTCT measurements

- **Test structure**
 - 3 x 3 pixel matrix without readout electronics
 - Central pixel to read out, outer pixels connected together
- **Irradiation**
 - Samples irradiated at TRIGA reactor in Ljubljana ($1E13$ to $2E5$ n_{eq}/cm^2)
- Depletion depth changes with irradiation + acceptor removal effects seen



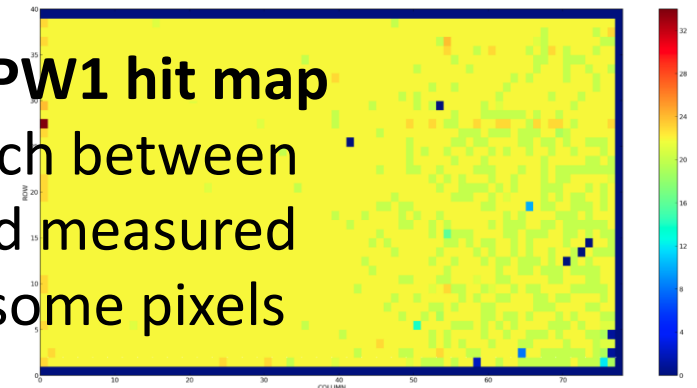
DAQ – Caribou (common projects 2021-01, 2023-04)

- **Xilinx Zynq-7000 SoC board**
 - ZC706 (ZC702 possible too)
 - Dual-core ARM Cortex-A9
 - Artix 7 FPGA
 - 2 FMC connectors, GbE, 1 GB DDR3 SDRAM, 128 Mb SPI flash memory, SD card, USB, etc.
- **Control and Readout (CaR) board**
 - Development of Brookhaven National Laboratory
 - Provides common services like power supplies, voltage outputs, ADCs, I2C bus, TLU input, etc.
- **Custom chip board**
 - Provides chip specific features
 - To be developed for each new device



RD50-MPW1 hit map

Mismatch between sent and measured hits in some pixels



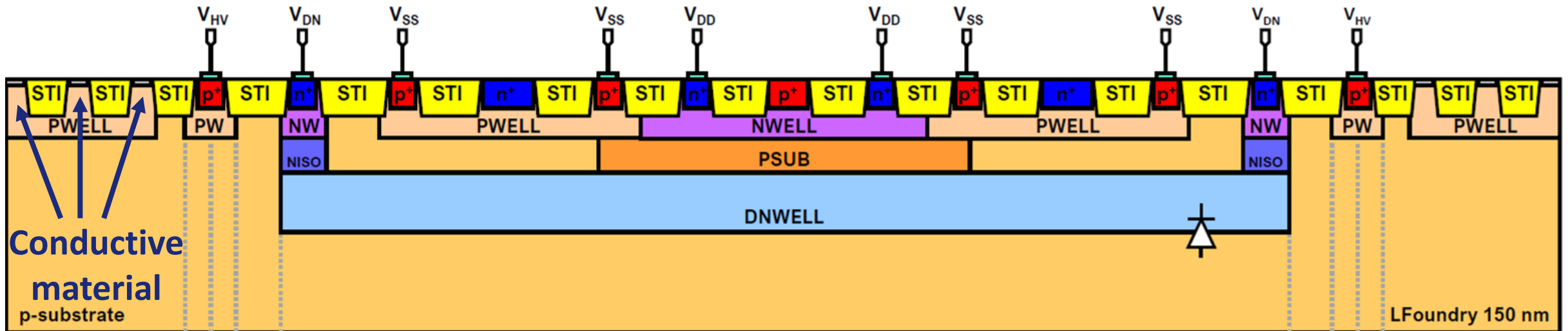
RD50-MPW1

- **First prototype was not great...**
 - It had bugs
- **Circumstances around its R&D...**
 - The technology process was new to us and we had to understand it
 - We did it the hard way
 - We developed all the IP from zero
 - This was a lot of work
 - RD50-MPW1 was a version zero chip
 - Yet ambitious chip
 - It implements advanced electronics (analog + digital readout) in a very small pixel cell (50 μm x 50 μm pixel), plus it has a digital interface
 - Small team

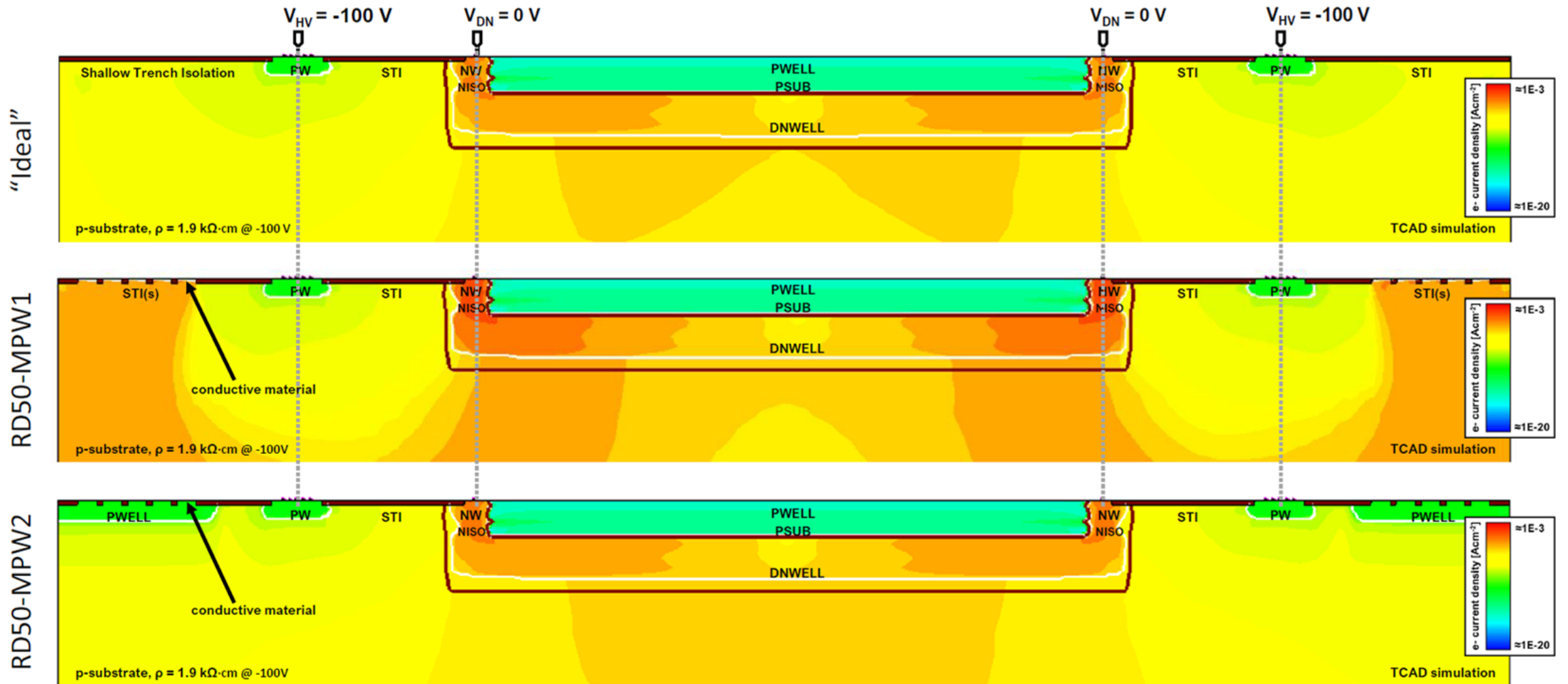


Towards RD50-MPW2 – Goal to minimise I_{LEAK}

- **The issue – what we learned from several discussions with the foundry (*)**
 - Structures involving conductive material are added to the design files to prepare them for fabrication (in the pixels, peripheral readout electronics, I/O pads, etc.)
 - These structures contribute quite significantly to the high I_{LEAK}
- **The solution – suggested by the foundry**
 - Minimise the presence of these structures as much as possible
 - Wherever not possible, place these structures inside a PWELL



The importance of TCAD simulations



Electron current density simulation

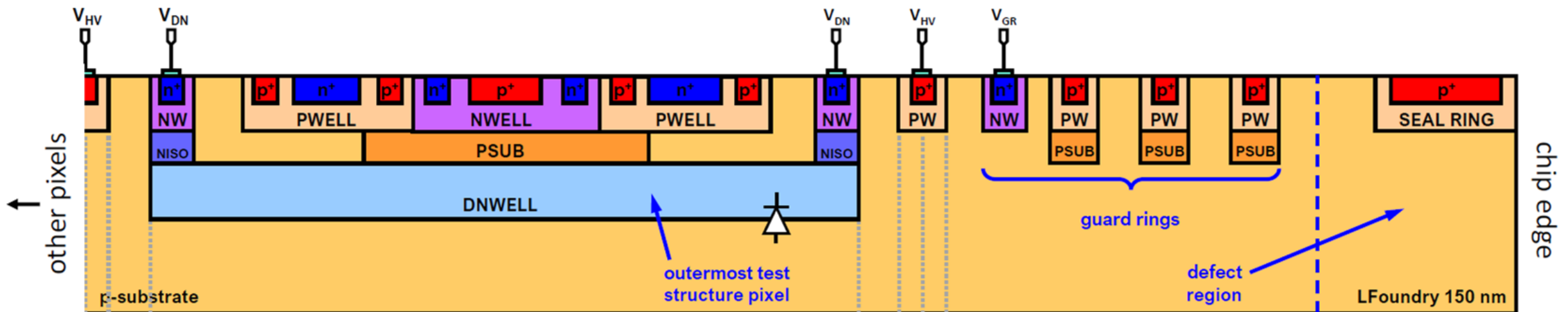
Towards RD50-MPW2 – Goal to minimise I_{LEAK}

▪ The issue

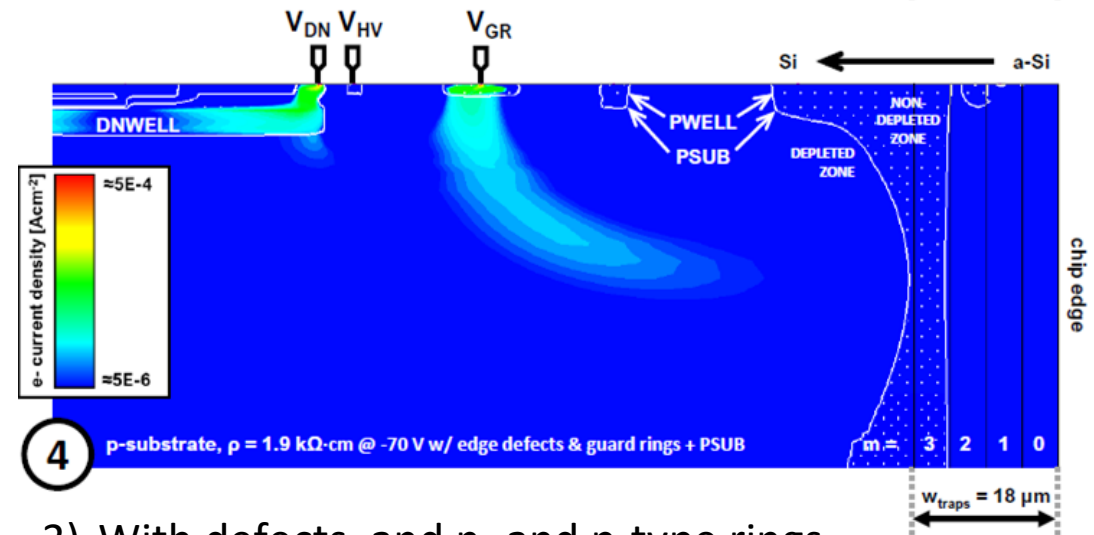
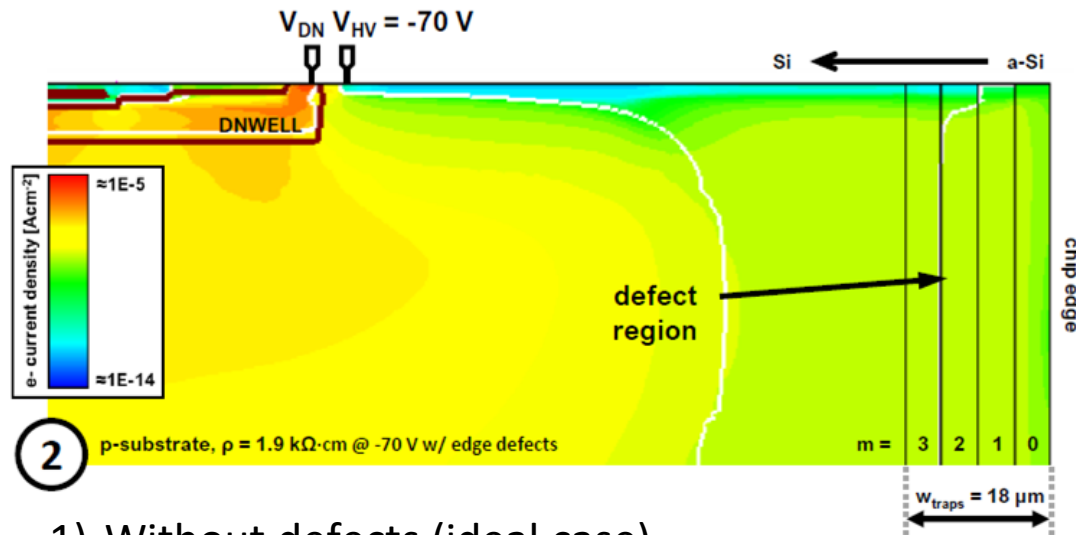
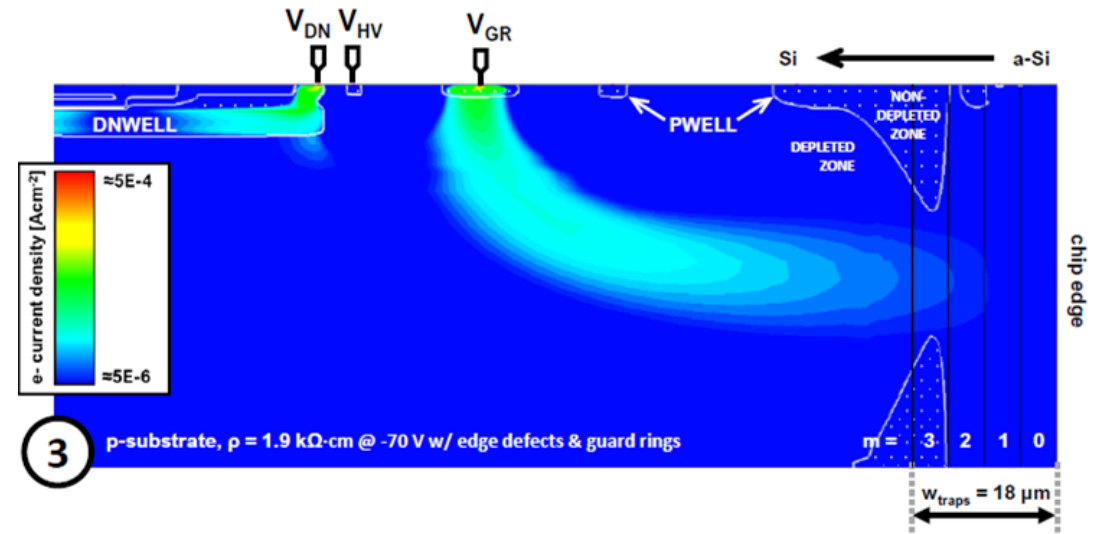
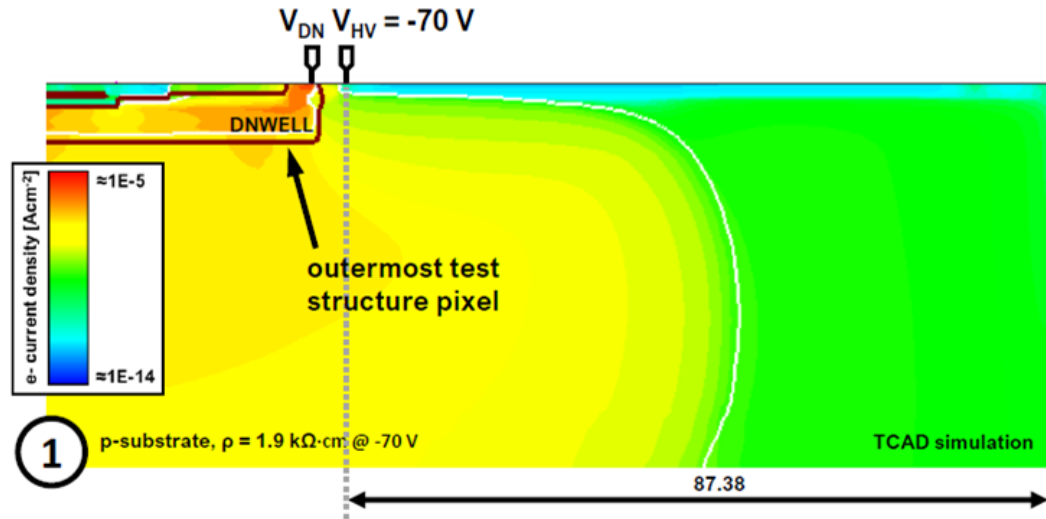
- Some pixels can be quite close to the edge of the chip
- Defects in silicon lattice due to dicing can become significant
- Leakage current increases when pixel depletion region is near the defect region

▪ The solution

- N-type guard ring as safeguard to “collect” leakage current
- P-type guard rings to reduce “chip lateral” depletion



The importance of TCAD simulations



1) Without defects (ideal case)

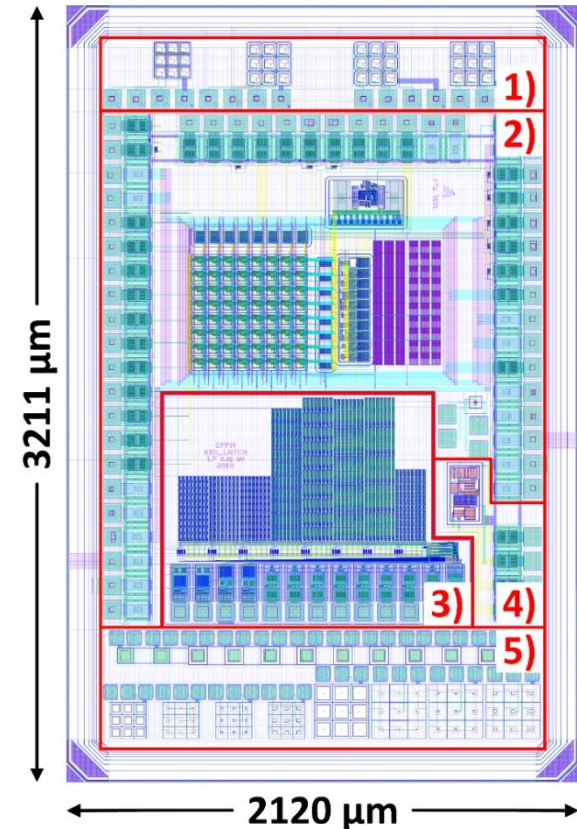
2) With defects and no guard rings

3) With defects, and n- and p-type rings

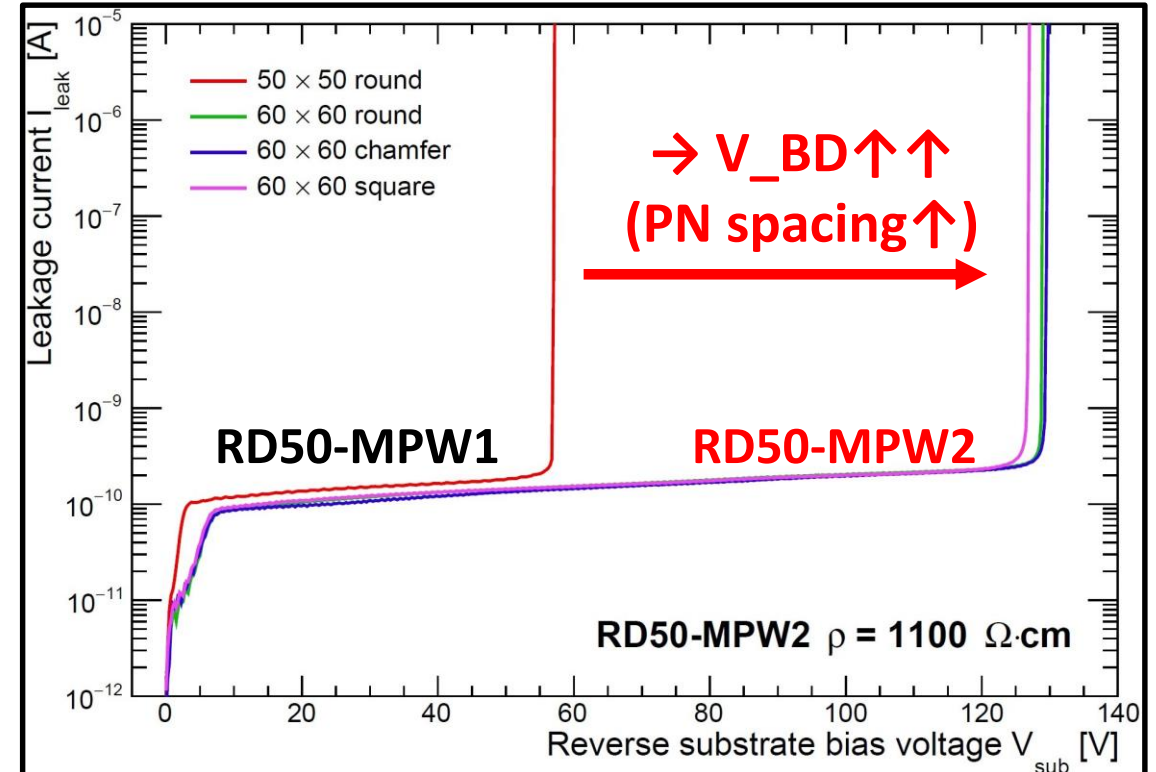
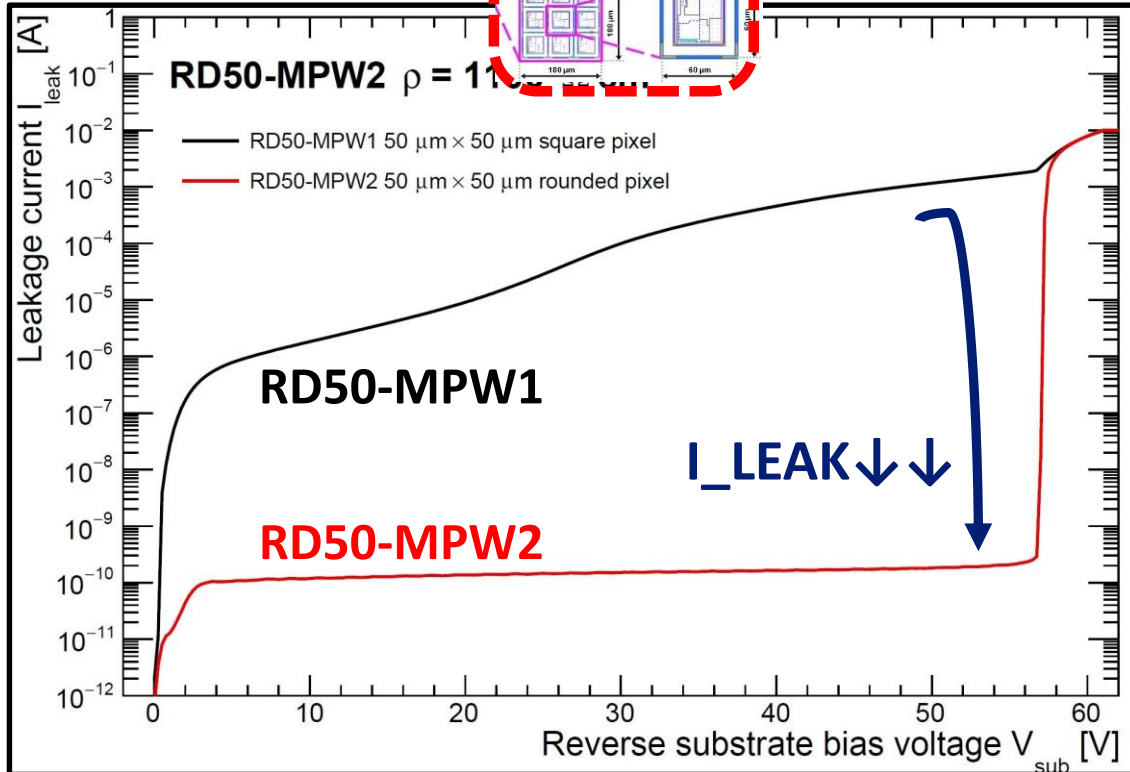
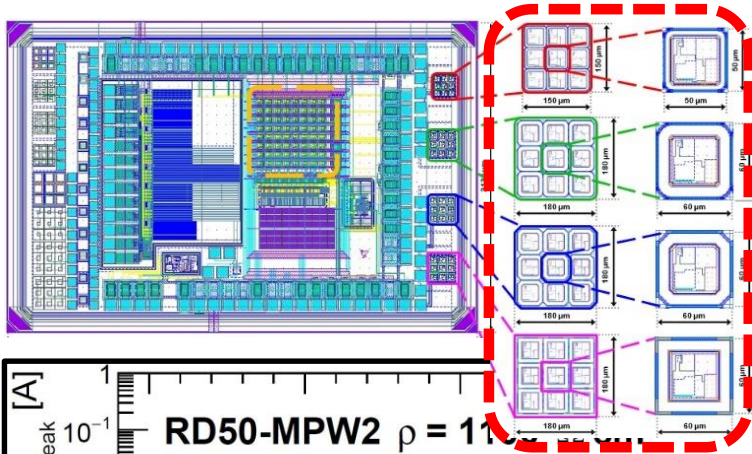
4) With defects, and n- and p-type (with deep p) rings

RD50-MPW2 (common project 2019-01)

- **Main goals**
 - To implement solutions to minimise high leakage current observed in RD50-MPW1
 - To test these solutions in a small matrix
- **Chip contents**
 - Tests structures with depleted CMOS pixels
 - Matrix of depleted CMOS pixels
 - 8 x 8 pixels (two pixel flavours)
 - 60 μm x 60 μm pixel area
 - Analog readout embedded in the sensing area
 - Matrix outputs are pixel amplifier and comparator (one pixel at a time), no digital readout
 - SEU tolerant memory array
 - Bandgap reference voltage
 - Test structures with SPADs and depleted CMOS pixels
 - Fabricated on standard, 100 $\Omega\cdot\text{cm}$, 1.9k $\Omega\cdot\text{cm}$ and 3k $\Omega\cdot\text{cm}$ wafers

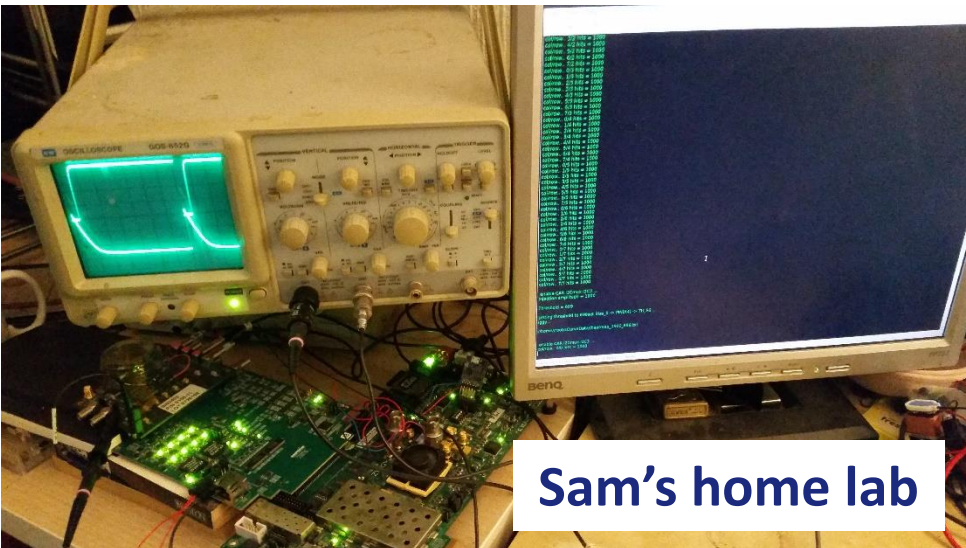


RD50-MPW2 – Current-to-voltage characteristics

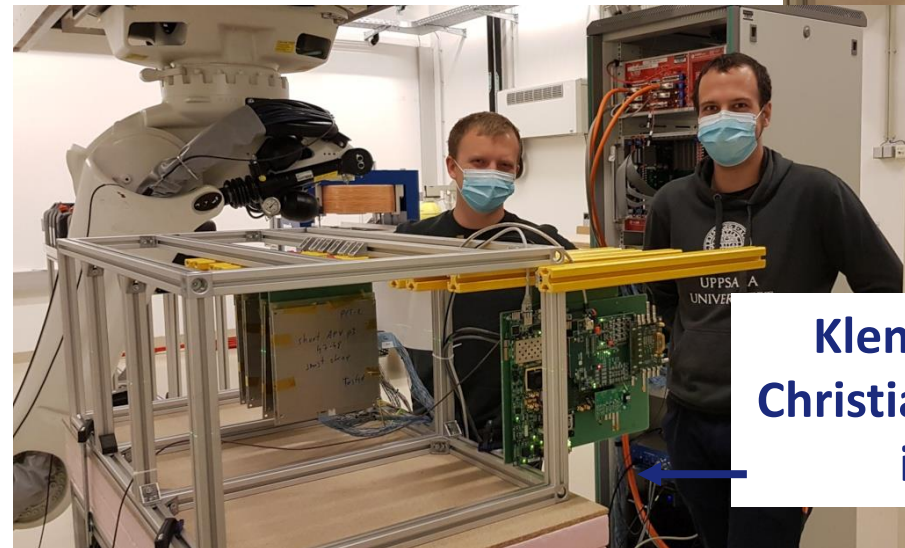


RD50-MPW2 – Crisis

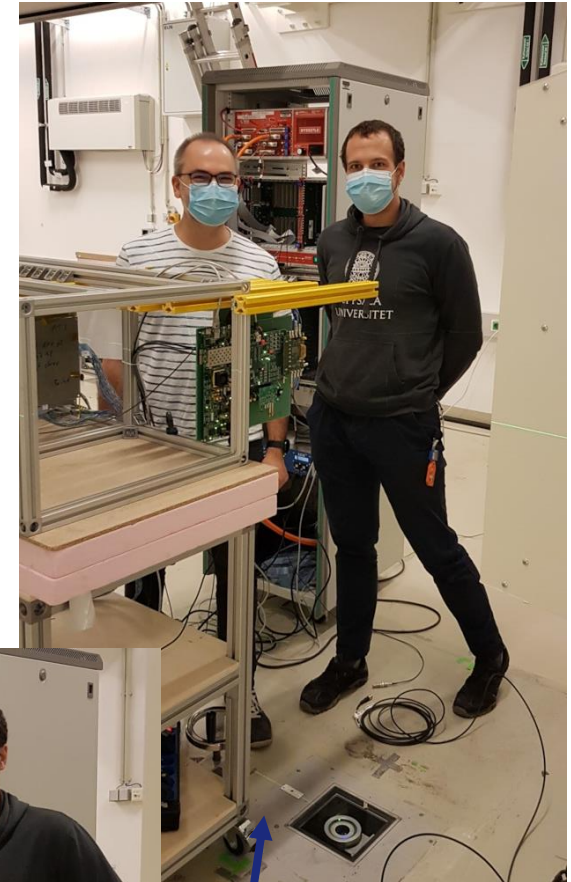
- **Fabrication delay**
 - Chip submitted in early 2019
 - Chip delivered in early 2020
 - Many months delay due to foundry refurbishment
- **Covid**
 - Many RD50-MPW2 measurements produced during lockdowns
 - People had test stands in their living rooms



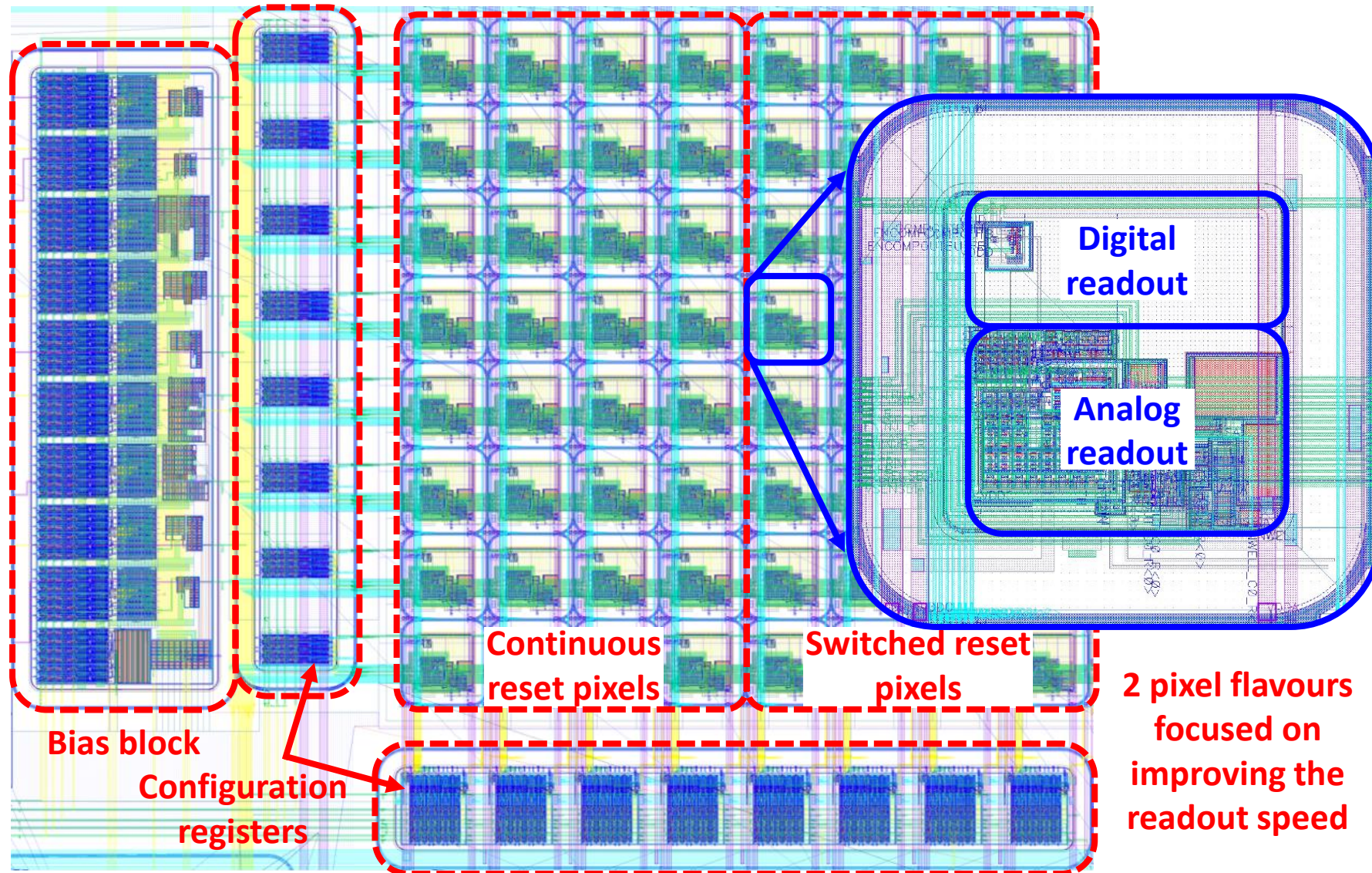
Sam's home lab



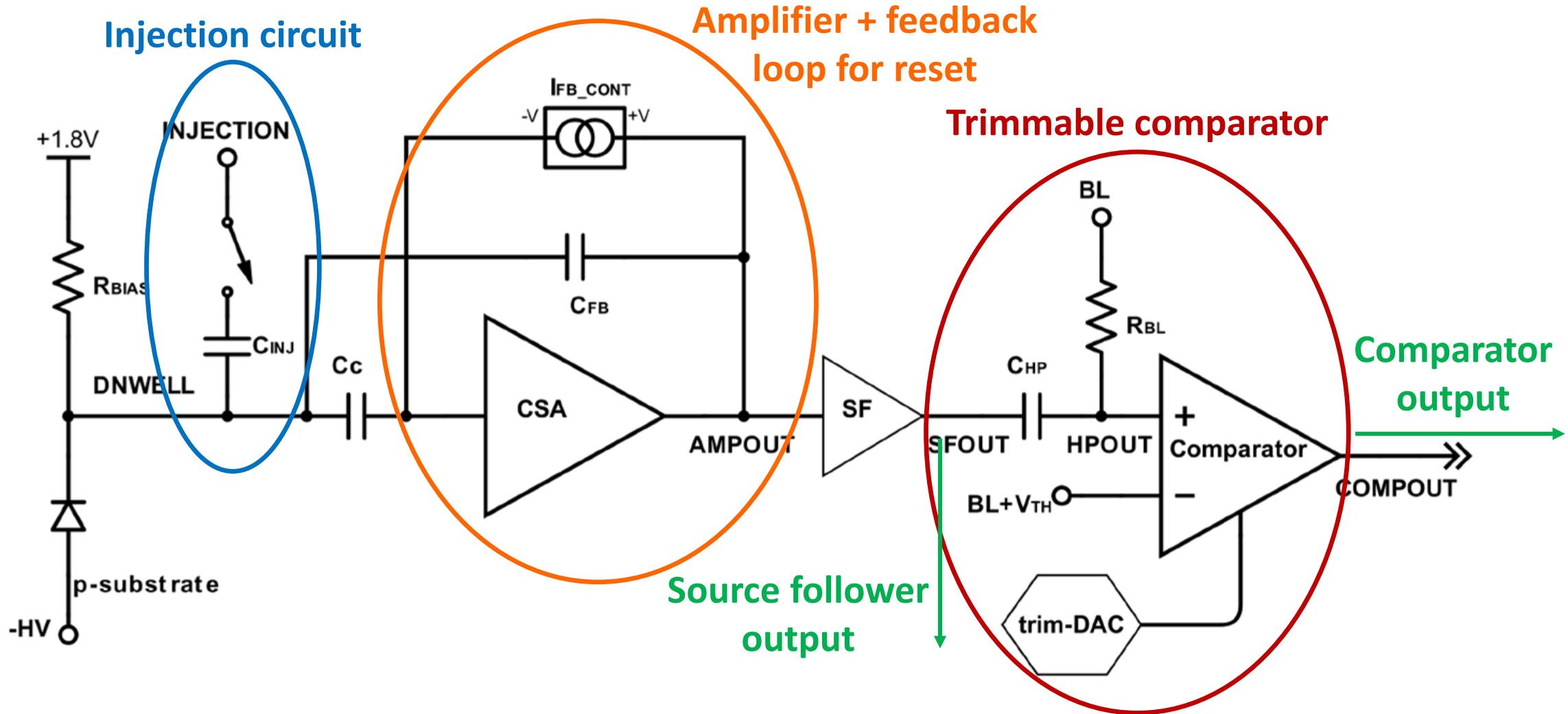
Klemens + Patrick +
Christian at MedAustron
in Dec 2020



RD50-MPW2 – Pixel matrix



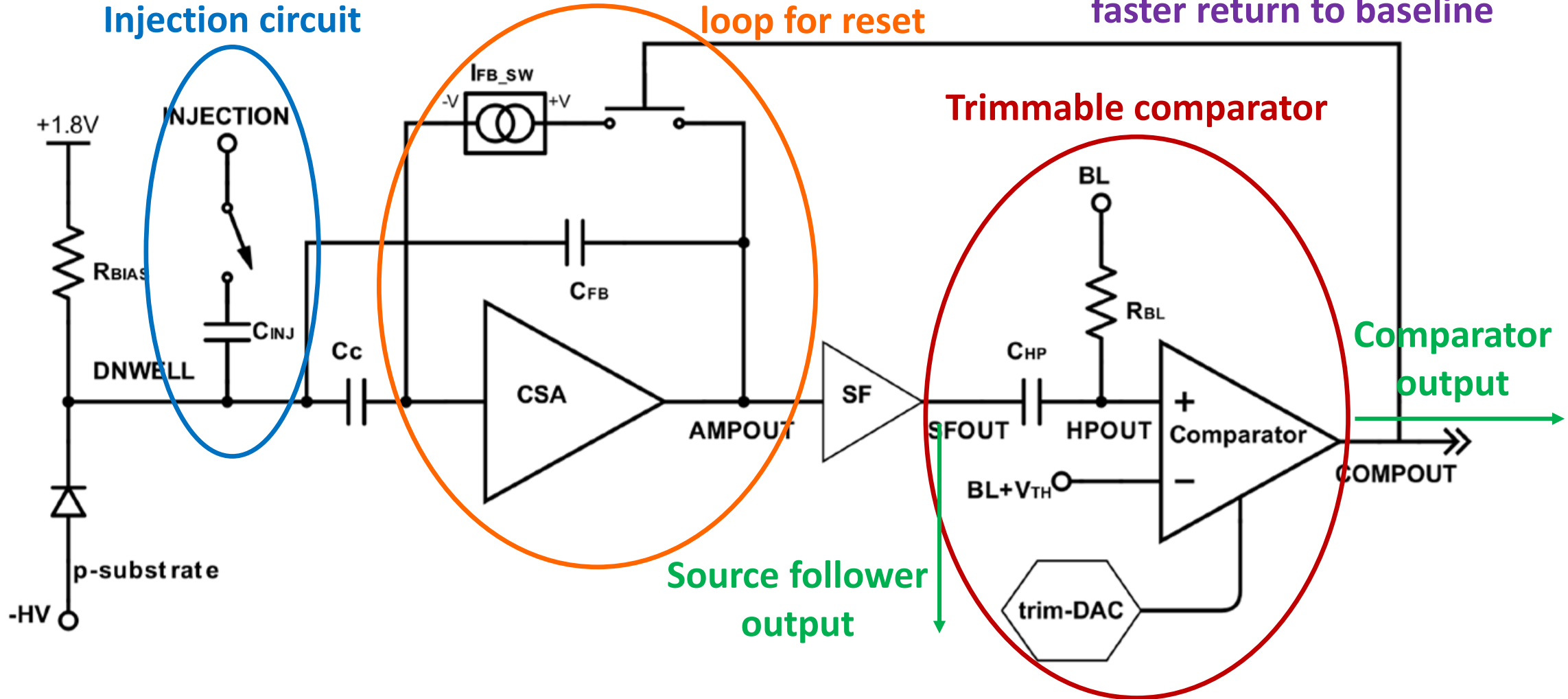
Pixel flavours – Continuous reset



Pixel flavours – Switched reset

Amplifier + feedback loop for reset

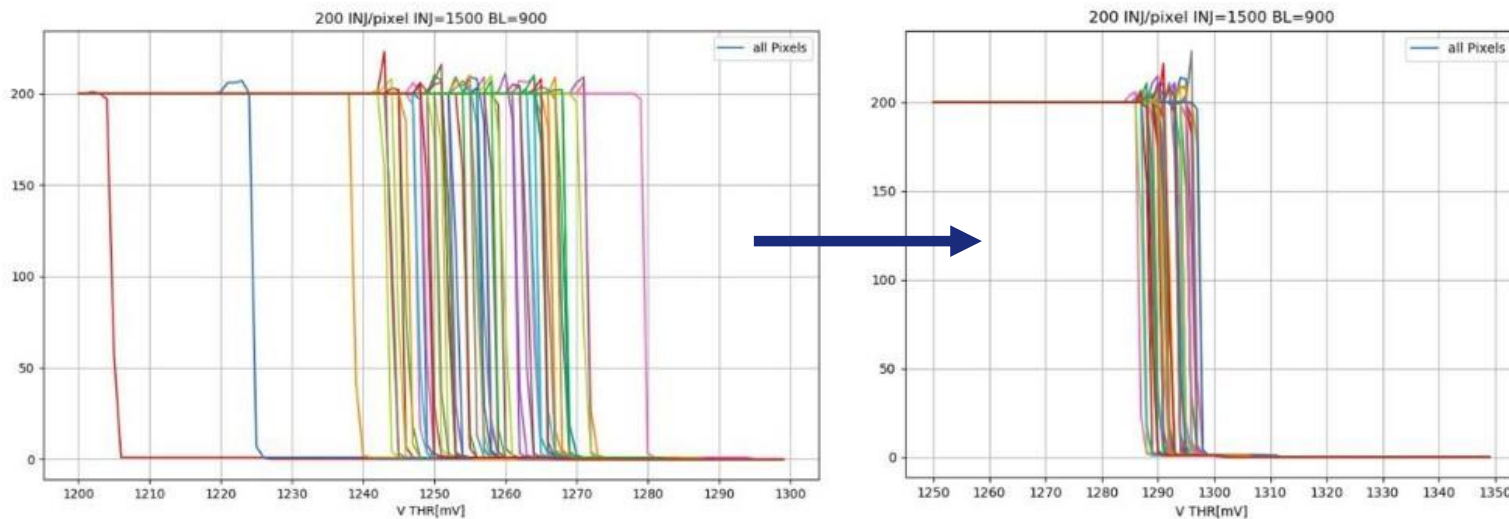
Additional, small current for faster return to baseline



RD50-MPW2 – Lab measurements: matrix electronics

- Many measurements of active pixel matrix
 - In-pixel calibration circuit (S-curves)
 - Pixel gain and noise
 - Trimming DACs
 - Response to radioactive sources
 - At several HV, before and after irradiation

S-curves for all pixels with threshold variation



Trim DAC value 15

Trim DAC values adjusted

RD50-MPW2 DAQ Caribou

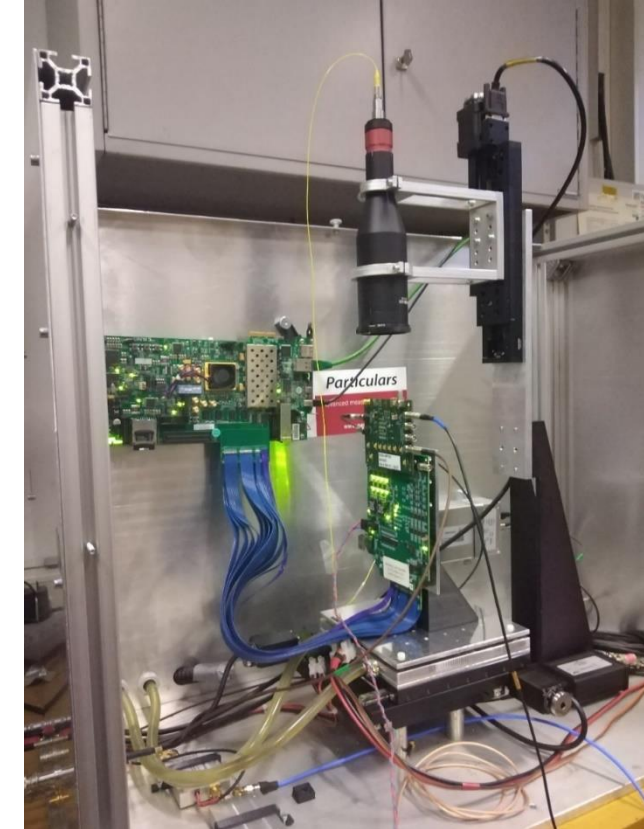
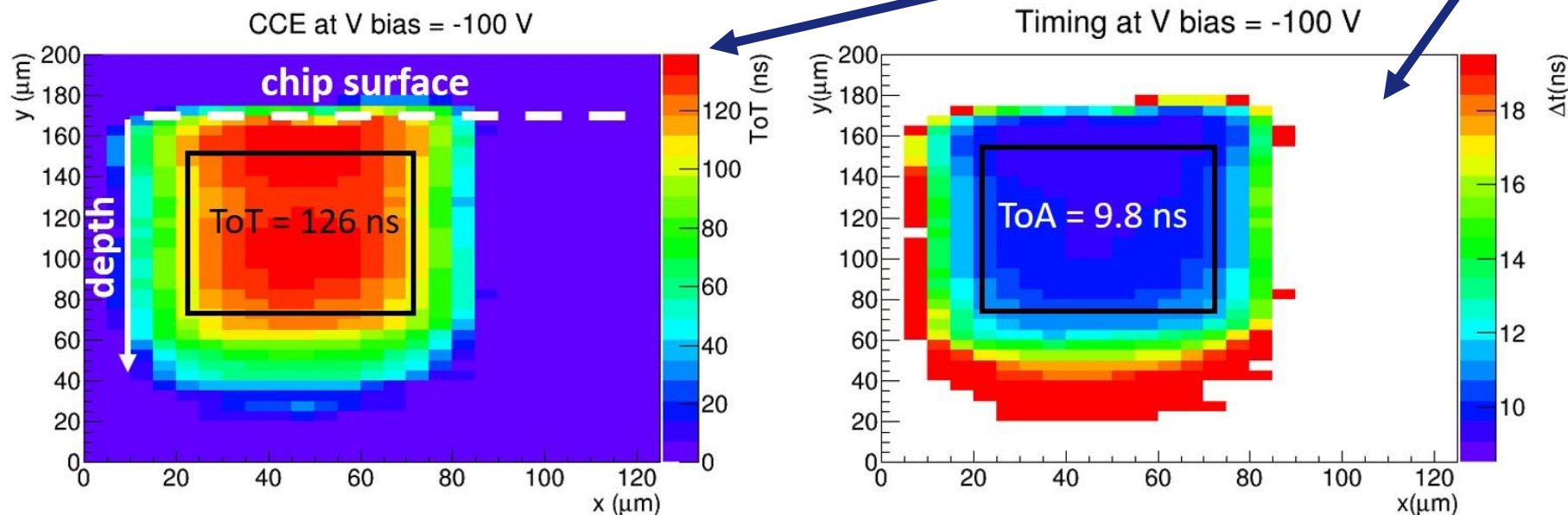


Chip board Control and Readout
(CaR) board

SoC board
(ZC706)

RD50-MPW2 – Lab measurements: timing

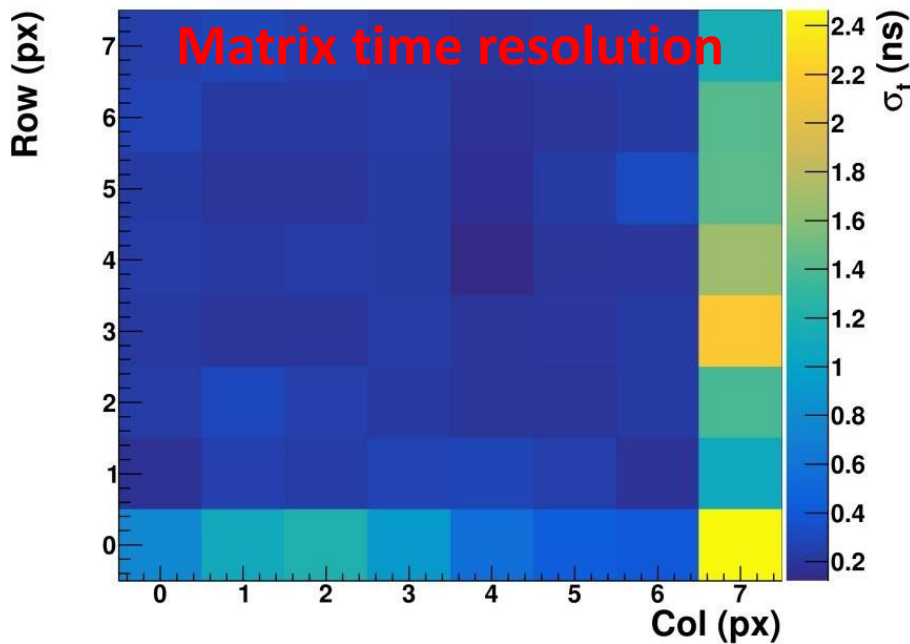
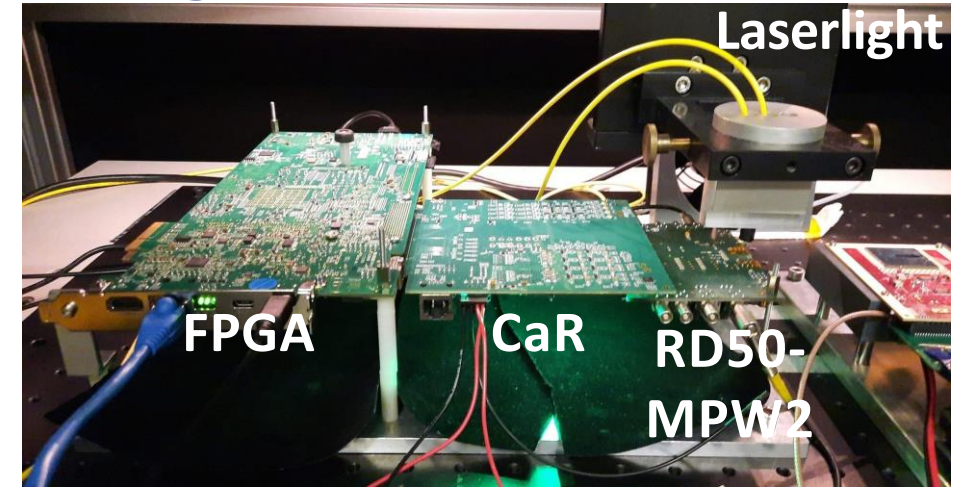
- **Main goal**
 - To study time-walk dependence on pixel position
- **Method and results**
 - Using edge-TCT setup
 - Measuring in-pixel comparator output
 - Evaluate average charge collection or ToT (L) and timing or ToA (R)



Evaluated volume: $50 \mu\text{m} \times 80 \mu\text{m}$ (W x H), starting $20 \mu\text{m}$ below the surface

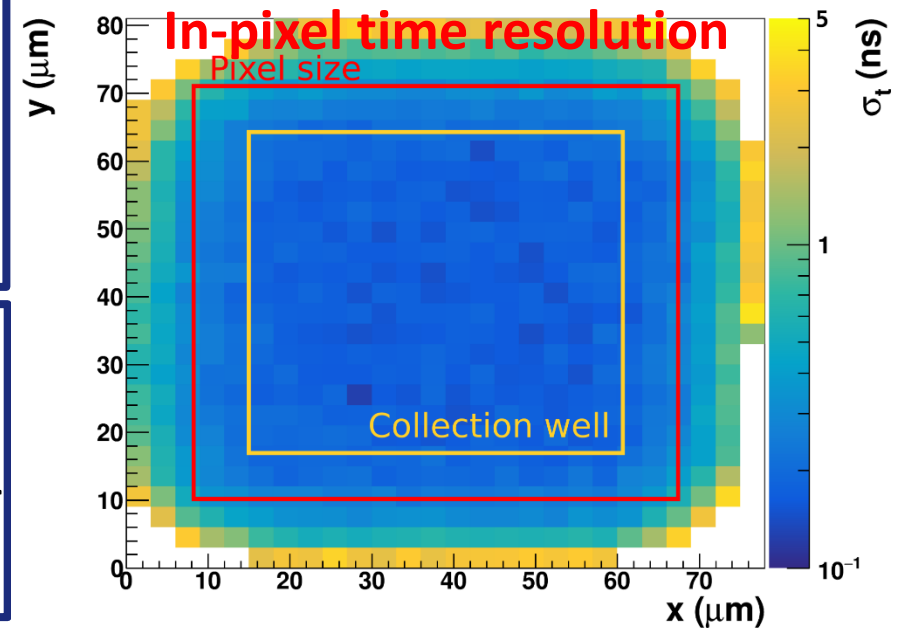
RD50-MPW2 – Lab measurements: timing

- **Goal**
 - To study matrix and in-pixel time resolution
- **Method**
 - Using edge-TCT setup (back measurements)
 - Measuring rising time of in-pixel comparator output and comparing it against laser pulse



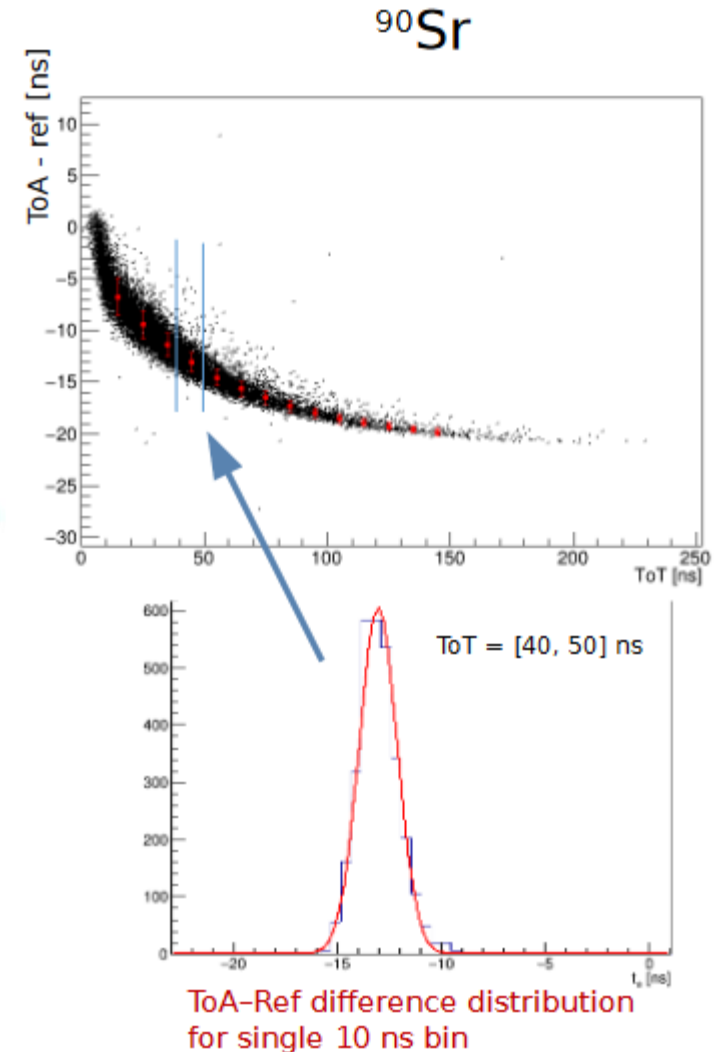
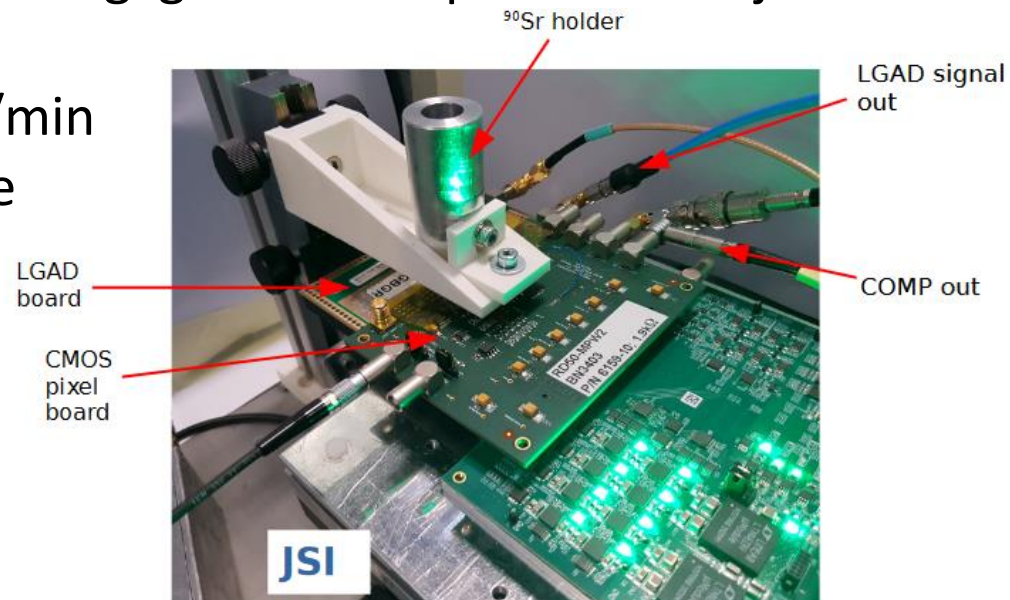
$\sigma_{\text{switched}} = 211 \pm 45 \text{ ps}$
 $\sigma_{\text{continuous}} = 227 \pm 27 \text{ ps}$
Switched reset pixels have slightly better time resolution

$\sigma_{\text{switched}} = 250 \pm 42 \text{ ps}$
 $\sigma_{\text{continuous}} = 267 \pm 56 \text{ ps}$
Better time resolution under collection well



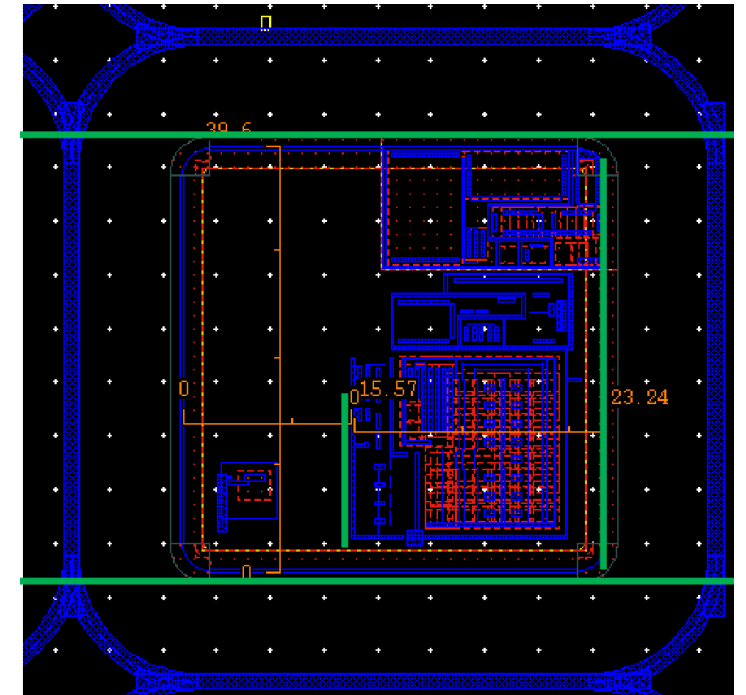
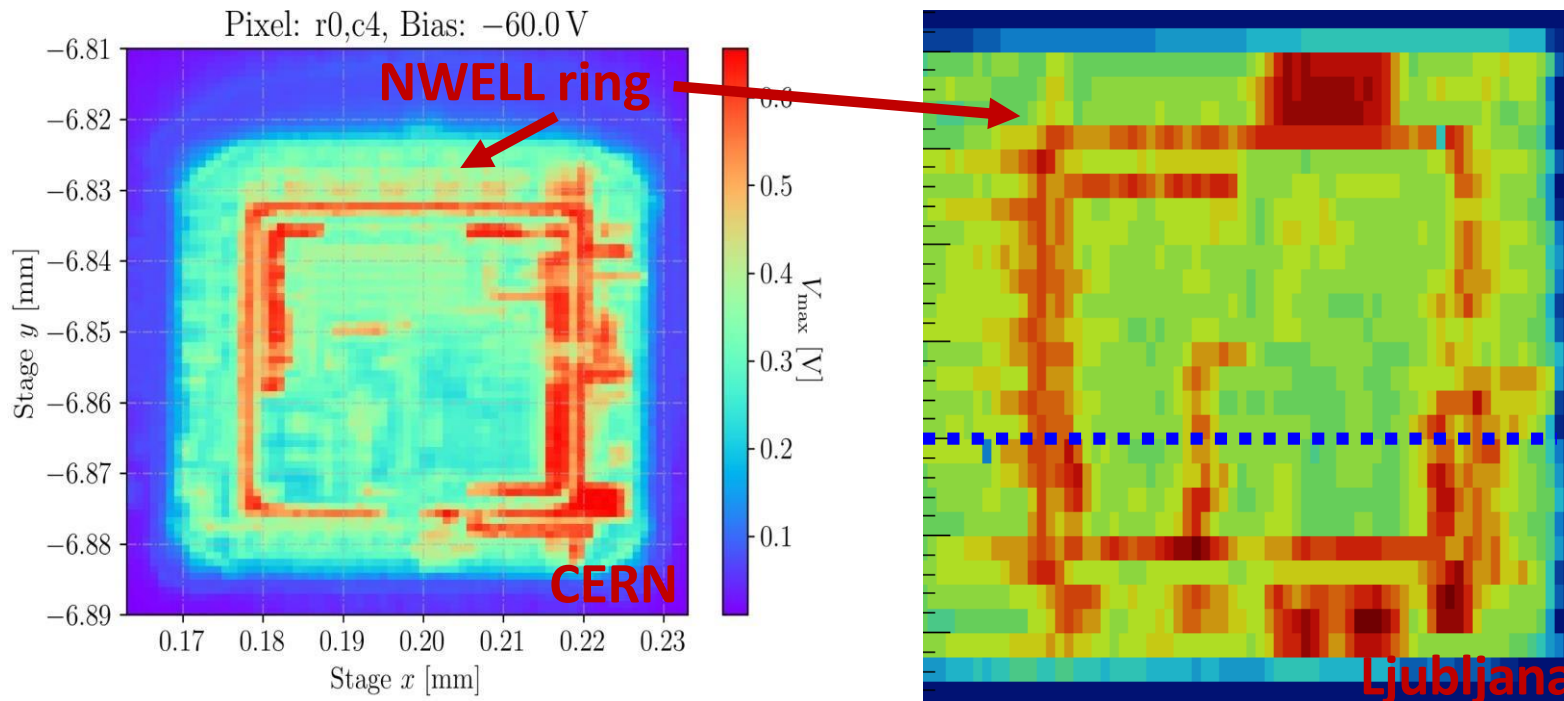
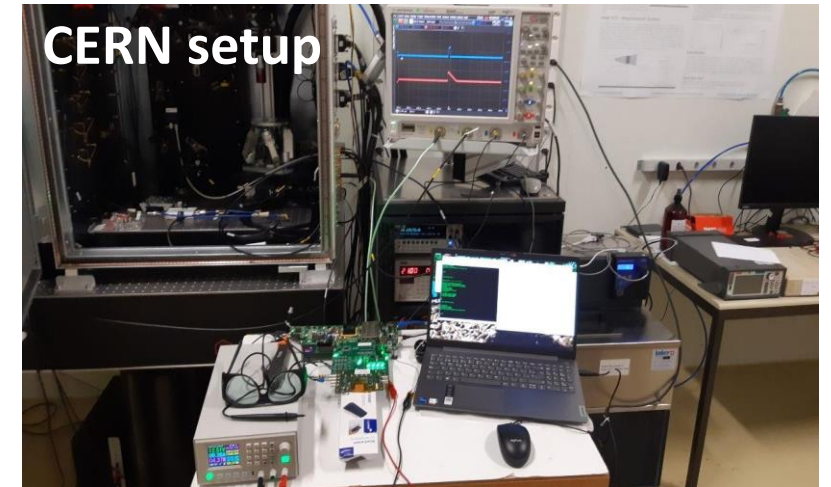
RD50-MPW2 – Lab measurements: timing

- **Goal**
 - Timing measurements with ^{90}Sr source
- **Method**
 - Reference signal from 1 mm x 1 mm LGAD detector behind the CMOS chip
 - Trigger: sample + LGAD
 - LGAD jitter of ~ 30 ps negligible in comparison with jitter of CMOS pixel
 - Low rate: ~ 1 event/min with 18 MBq source



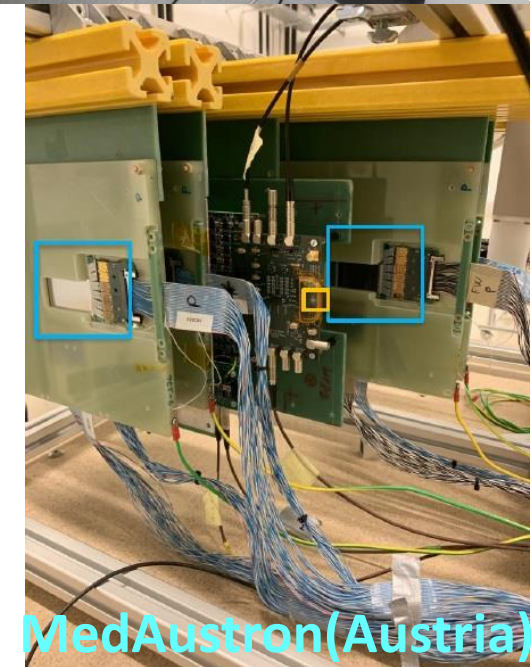
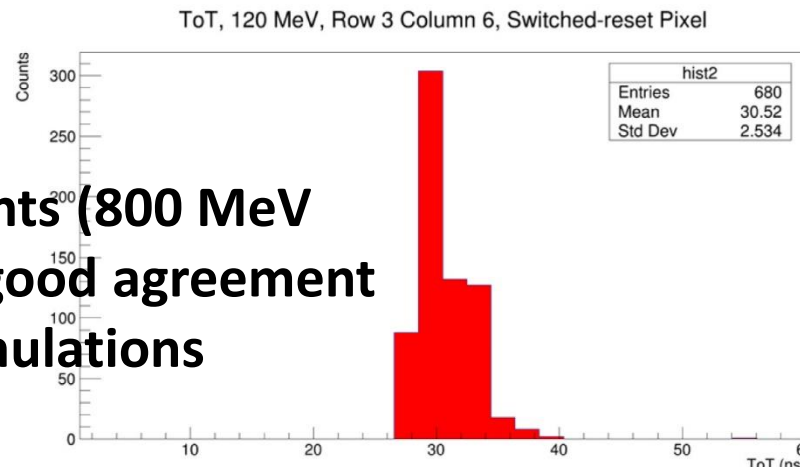
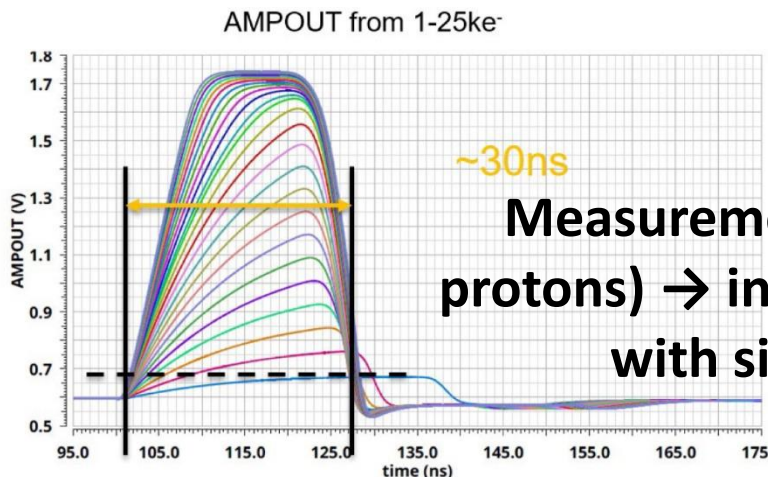
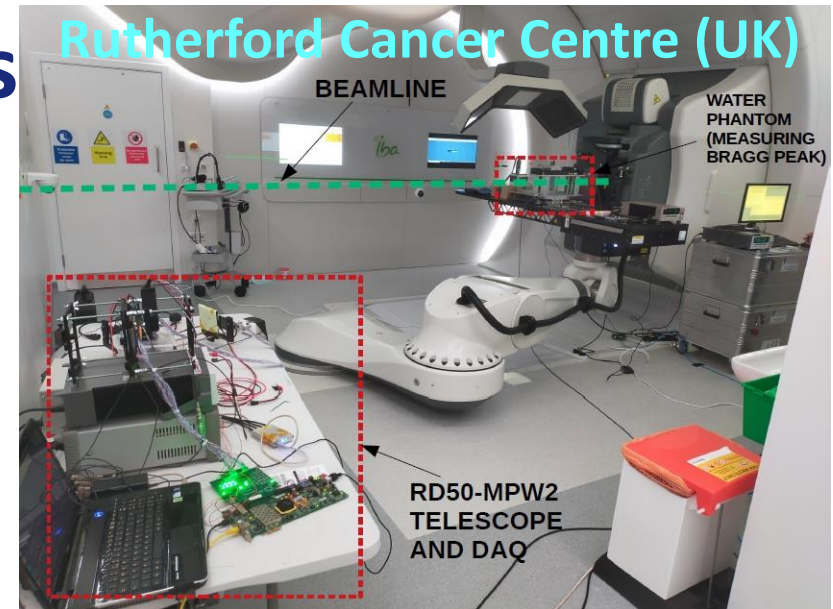
RD50-MPW2 – Used with TPA laser

- **Goal**
 - To study pixel matrix and setup equipment
- **Method**
 - High precision xy probing of in-pixel structure
 - Detailed map of the electric field

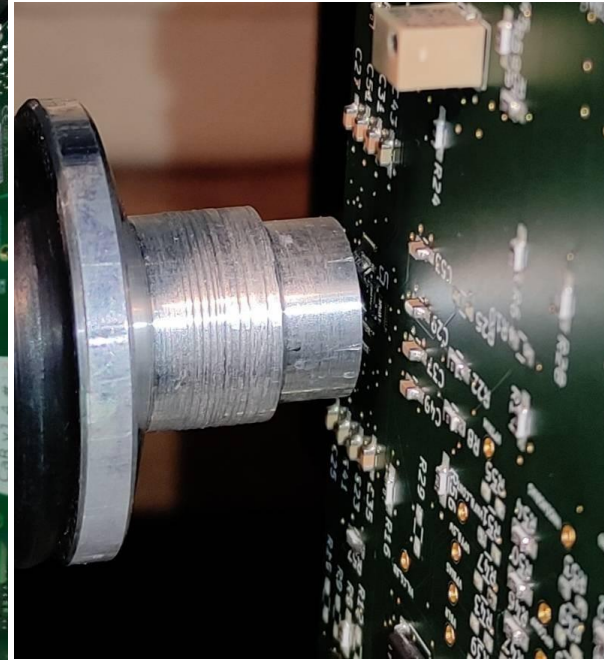


RD50-MPW2 – Test beams with protons

- **Main goals**
 - To integrate RD50-MPW2 into test beam data acquisition system and evaluate the chip with a particle beam
- **Methods**
 - Switched reset pixel
 - ToT in simulations ~ 30 ns (for all energies)
 - Standalone firmware (counter in FPGA)
 - Double sided silicon strip detectors as trigger
 - Triggered by coincidence with AIDA-TLU

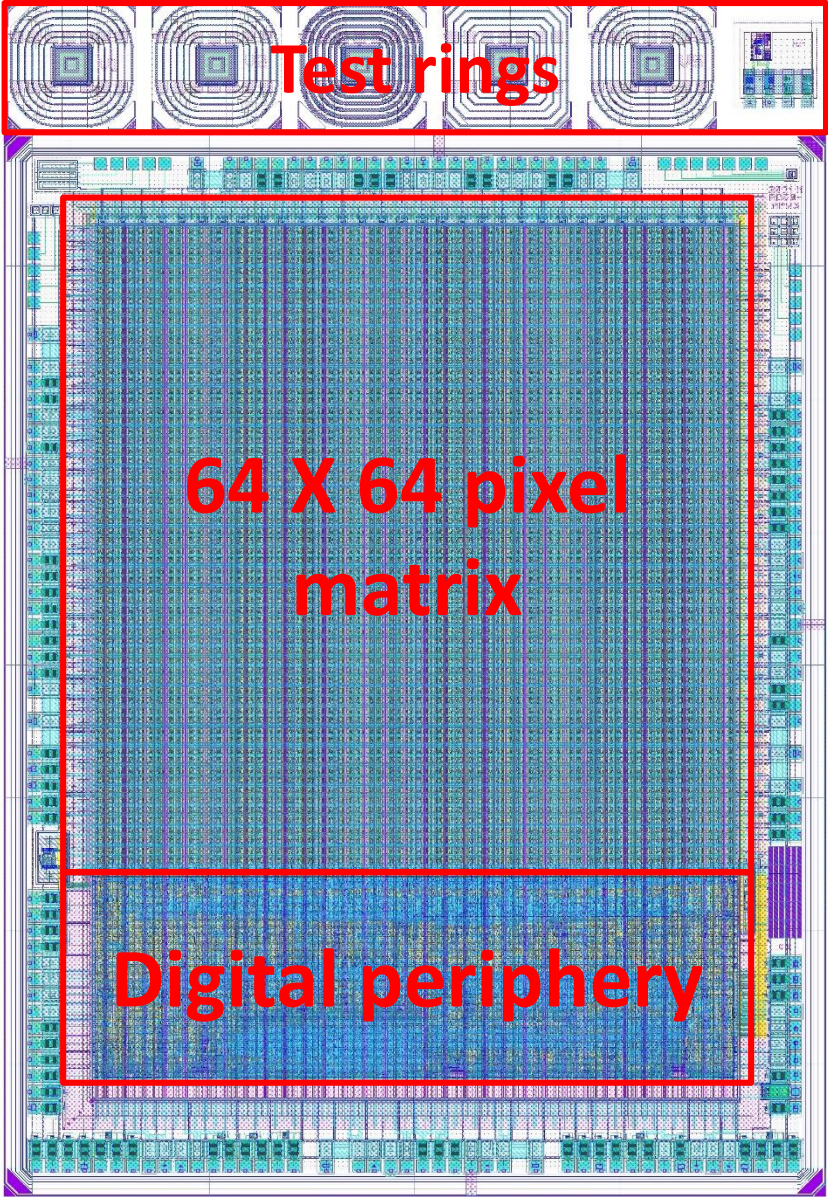


RD50-MPW2 – Test beam with ions



- **At RBI in Zagreb (ion microbeam facility)**
 - To see SEU events
 - To measure pixel CCE





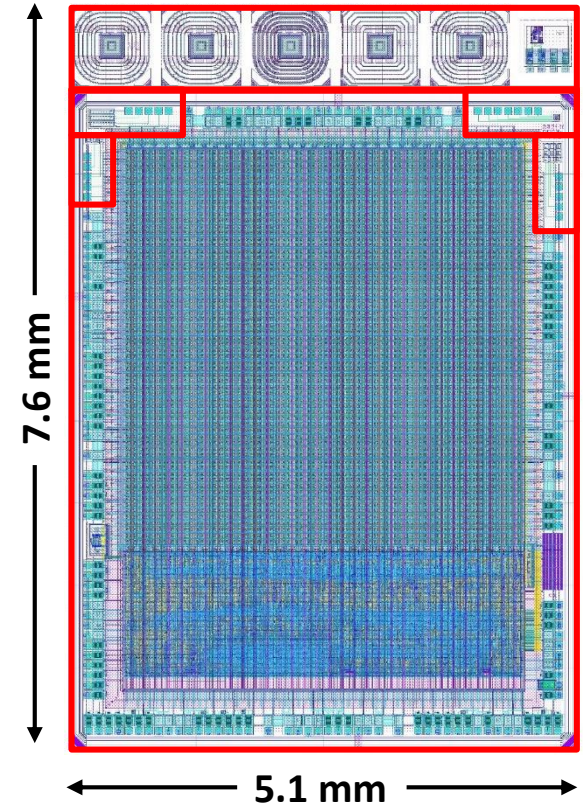
RD50-MPW3 (common project 2021-04)

■ Main goals

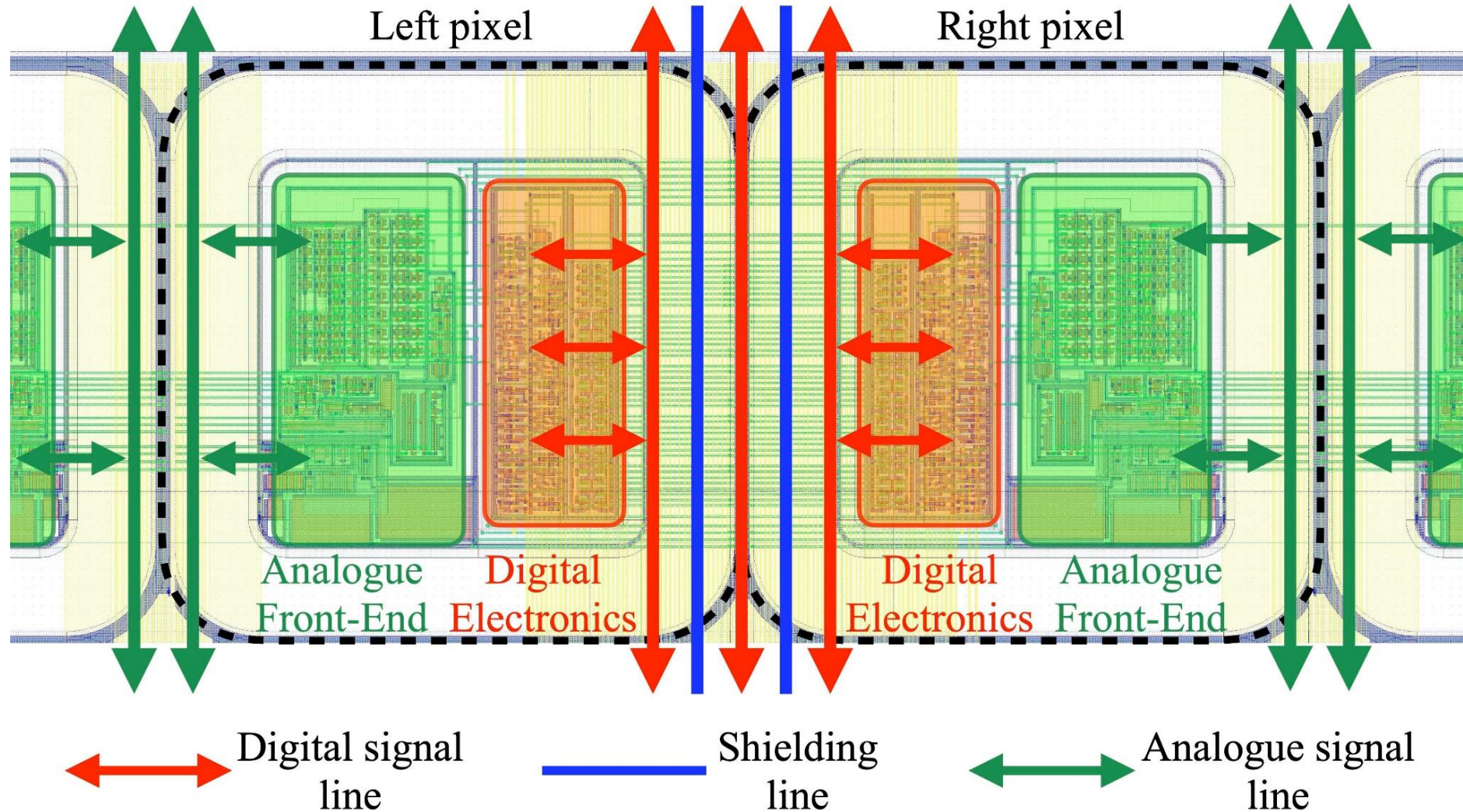
- To extend the number of pixels in the active matrix to perform advanced measurements (e.g. test beams)
- On-chip in-pixel column drain digital readout electronics (FE-I3 style)
- On-chip digital periphery for effective pixel configuration and fast data transmission

■ Chip contents

- Matrix of depleted CMOS pixels with FE-I3 style readout
 - 64 x 64 pixels
 - 62 μm x 62 μm pixel area
 - Analog and digital readout embedded in the sensing area
 - Double column scheme to alleviate routing congestion and minimise crosstalk
 - Digital periphery with I2C, Wishbone bus and one LVDS link
- Tests structures (top band with chip rings, e-TCT, DLTS)
- Fabricated on standard, 1.9k $\Omega\cdot\text{cm}$ and 3k $\Omega\cdot\text{cm}$ wafers



Pixel layout



Double column scheme to alleviate routing congestion and minimise crosstalk

Towards RD50-MPW3 – The hidden things

▪ Cadence Design Share Agreement

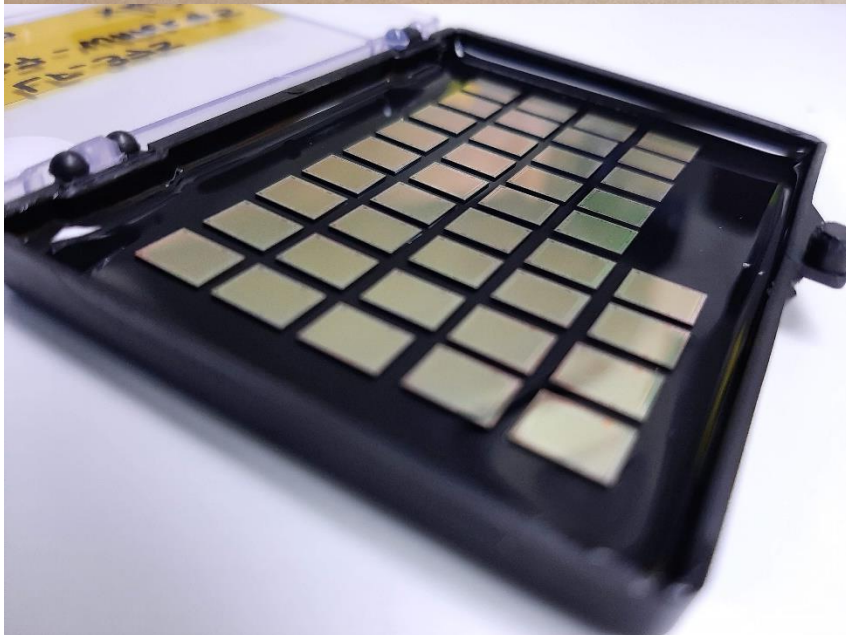
- Agreement between Cadence and organisations who wish to share Cadence produced design files between them (managed by Europractice)
- It took us one year to understand how it works
- The agreement uses a bi-directional all-connected topology
 - n institutes $\rightarrow n*(n-1)$ Design Share Agreements
 - 7 design institutes in RD50-MPW3 \rightarrow 42 agreements!
- The agreement model changed after RD50-MPW3

▪ ClioSoft SOS repository

- Software integrated within Cadence for sharing design files between remote organisations
- We use it for analogue design files and all layout views
- We set up a SOS server, to which all the remote organisations connect

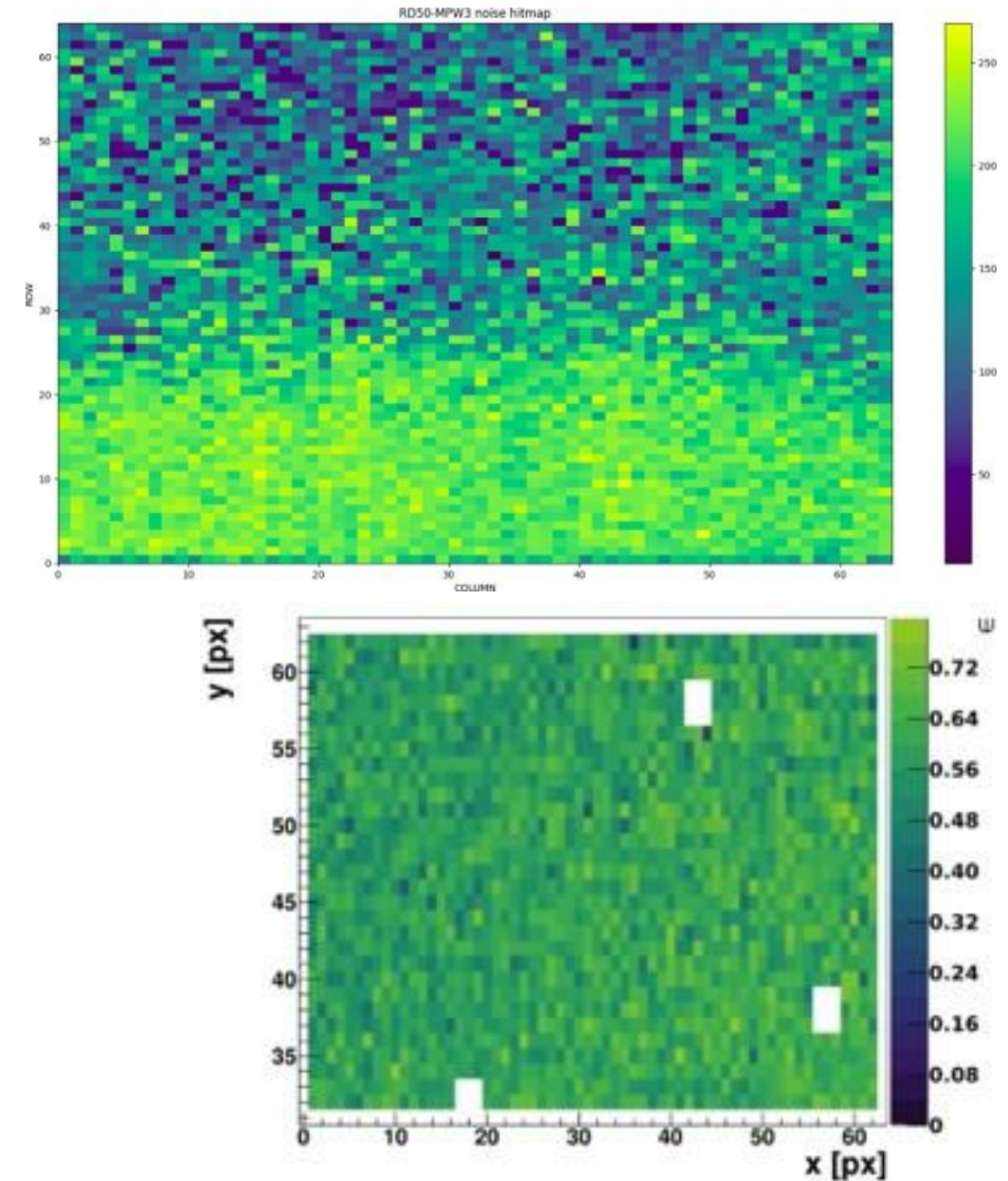
▪ GitLab repository

- We use it for digital design files and all layout views
- And also for DAQ firmware and software



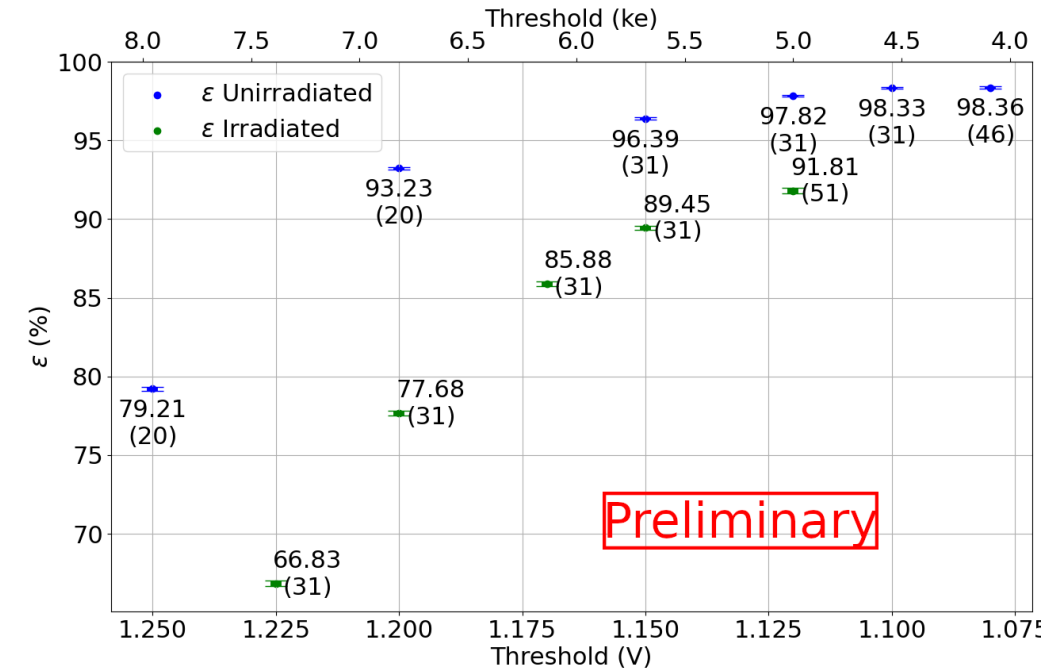
RD50-MPW3 – Test beams

- **Main goals**
 - To integrate RD50-MPW3 into reference system while enabling synchronisation between the chip and AIDA2020 TLU
 - To evaluate the chip with a particle beam
 - To form an effective RD50 CMOS test beam crew
- **Methods and results**
 - CERN SPS (120 GeV electrons and pions)
 - Mimosas-26 planes controlled by EUDAQ2
 - Autumn 2022
 - High threshold voltage due to high noise especially for those pixels that are near the digital periphery (and synchronisation problem in the DAQ)
 - Average chip efficiency ~60%



RD50-MPW3 – Test beams

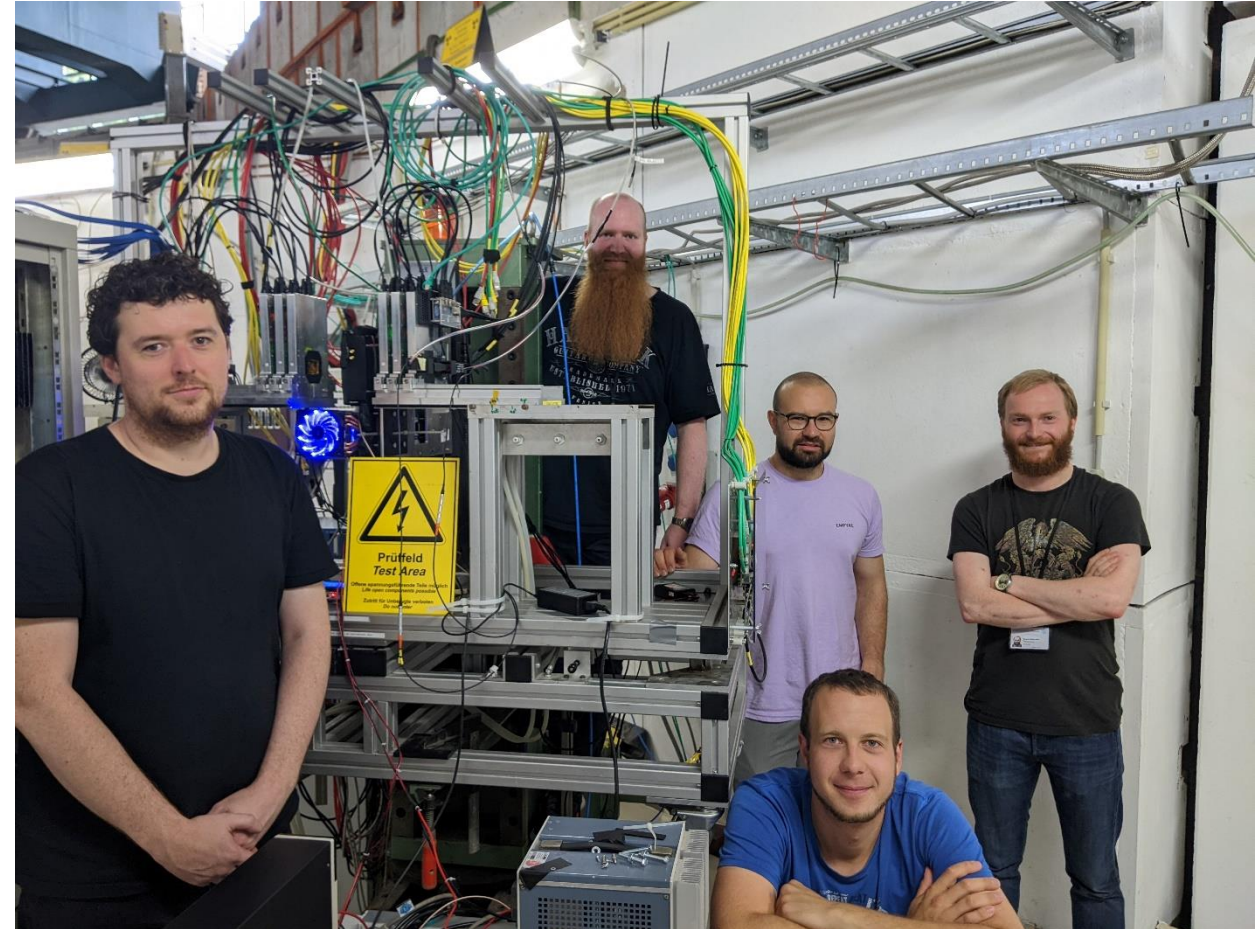
- **Main goals**
 - To evaluate the chip (with an improved DAQ) with a particle beam
 - To evaluate irradiated samples ($1E14 n_{eq}/cm^2$)
- **Methods and results**
 - DESY (4.2 GeV electrons)
 - Adenium telescope
 - Summer 2023
 - High noise half matrix was ignored
 - Synchronisation issue was solved
 - Average chip efficiency $\sim 98.3\%$ (before irradiation)
 - (other test beams at MedAustron)



RD50-MPW3 – Test beam team

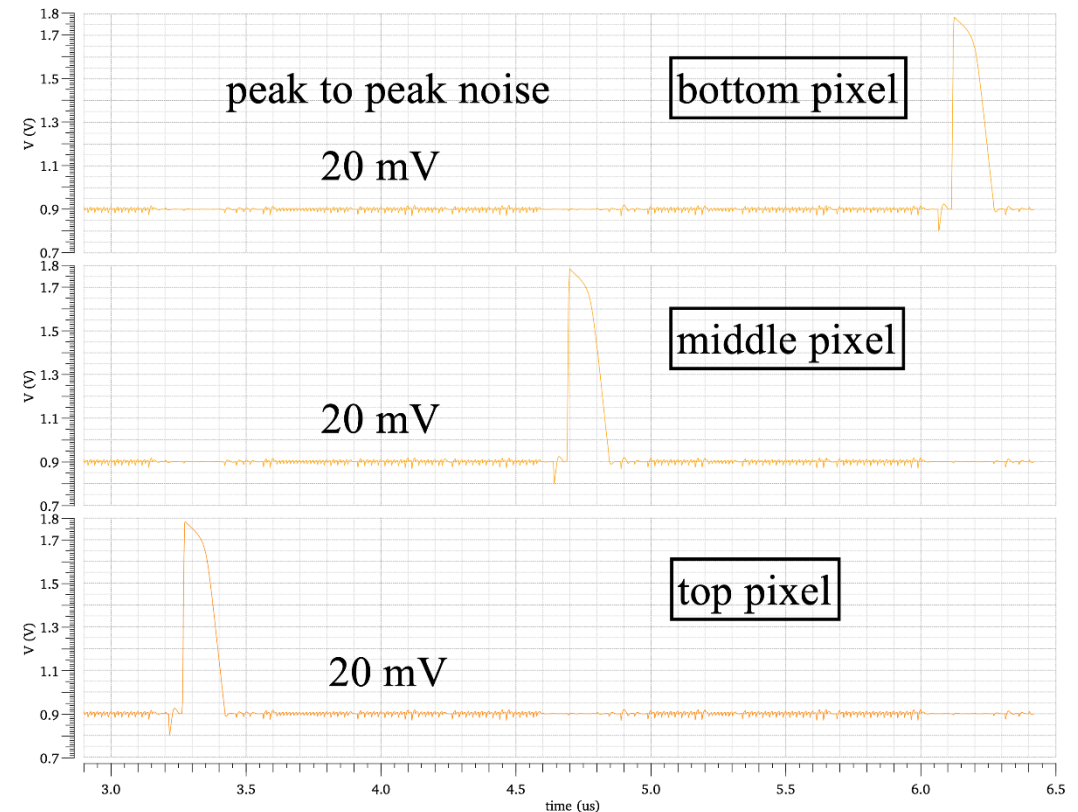
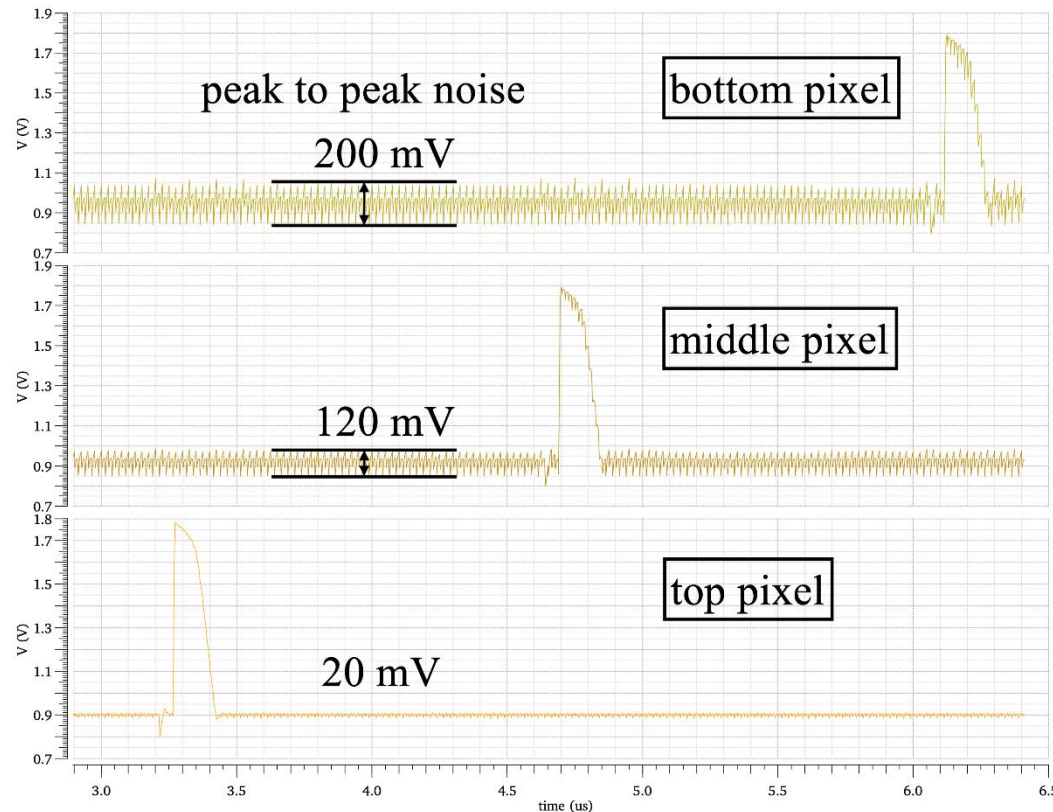


CERN, autumn 2022



DESY, summer 2023

The importance of post-layout simulations

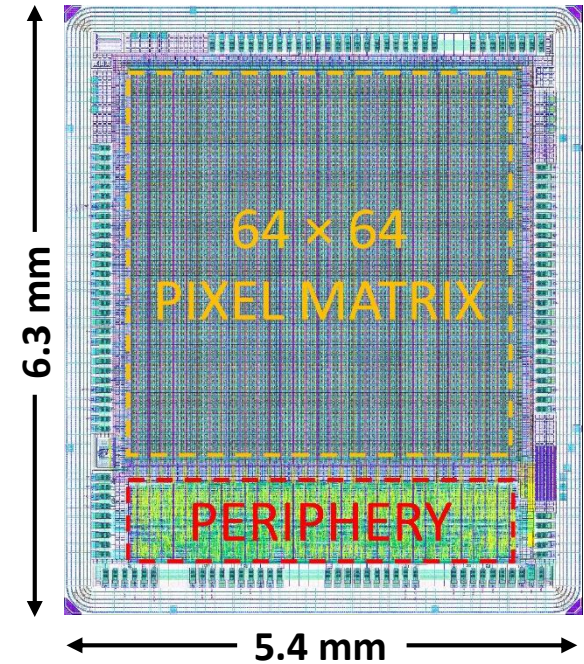


- Simulated analogue output signals of pixels from different locations
 - **Left** The pixel matrix and readout periphery share the same digital power and ground
 - **Right** The digital power and ground of the pixel matrix and periphery are separated

RD50-MPW4 (common project 2023-02)

■ Main goals

- To further improve the current-to-voltage-characteristics
 - Much higher V_{BD} (and much higher radiation tolerance)
 - New chip ring frame (test structure in RD50-MPW3)
 - Chip substrate biasing with topside edge contacts or backside contacts
- To achieve low-noise by separating the digital in-pixel and digital peripheral power and ground domains
- To reduce the size of the digital periphery
- To fix small design bugs



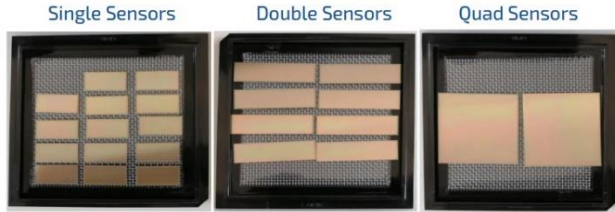
■ Chip contents

- Matrix of depleted CMOS pixels with FE-I3 style readout
- Tests structures (e-TCT, DLTS)
- Fabricated on standard and 3k $\Omega\cdot\text{cm}$ wafers
- Backside biasing is possible

To be delivered very soon... stay tuned!

FULL-SIZE SUBMISSION FOR ATLAS ITK

- Frontside process: Reticle stitching for large sensors
- Wafers received backside processing
- **150 um thick Float-Zone** wafers instead of Czochralski wafers



Wafer layout



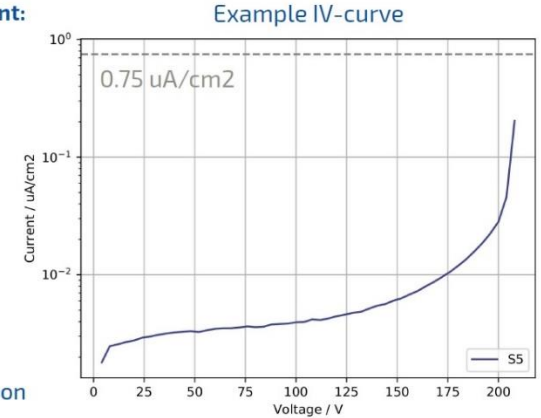
- Not only pixel sensors, also strip sensors: [Talk by Jan Cedric Honig](#)

Work done with: A. Macchiolo, D. Münstermann, M. Backhaus

IV-CURVES: FULL-SIZE ATLAS ITK SENSORS

- Had issue with backside processing leading to increase of current when depletion zone touches the backside
- **Solved by increasing the implant-dose of backside implant:**
 - Keeps depletion zone away from damaged silicon at backside
- Sensor requirements:
 - $V_{dep} \sim 30V (< 100V, \text{ for } 150 \mu m)$ ✓
 - $I_{leak} < 0.75 \mu A/cm^2 @ 80V (V_{dep} + 50 V)$ ✓
 - $V_{break} \sim 200-180 V (> V_{dep} + 70 V)$ ✓

→ **Sensors fulfill specifications**
- Measurements on irradiated samples will be performed soon



LATEST MONOPIX PROTOTYPES

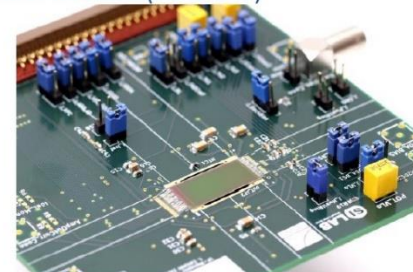
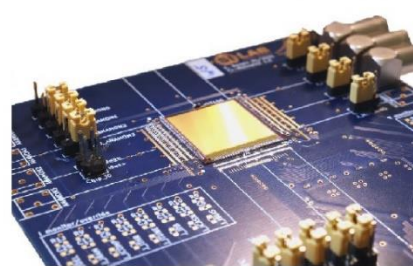
TJ-Monopix2:

- 180 nm TowerSemi CMOS technology
- Small collection electrode
- $2 \times 2 \text{ cm}^2$ matrix with $33 \times 33 \mu m^2$ pixel pitch
- Substrate resistivity $> 1 \text{ k}\Omega\text{cm}$

LF-Monopix2:

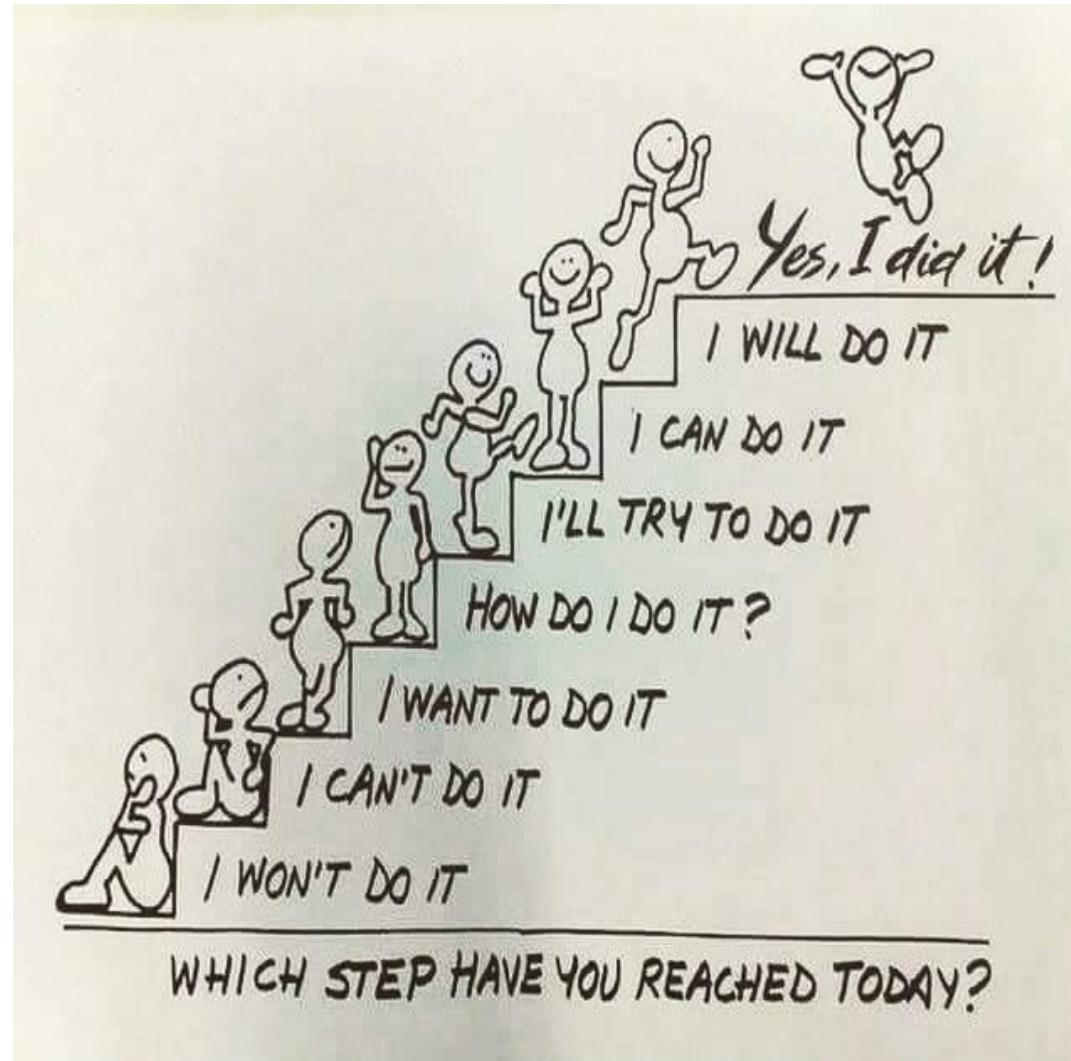
- 150 nm LFoundry CMOS technology
- Large collection electrode
- $2 \times 1 \text{ cm}^2$ matrix with $50 \times 150 \mu m^2$ pixel pitch
- Substrate resistivity $> 2 \text{ k}\Omega\text{cm}$

Same fast **column drain readout** architecture (FE-I3 like)



Summary

- 4 monolithic CMOS pixel chip prototypes + 1 DAQ (Caribou, and new Caribou)
- 17 institutes worldwide and approx. 50 people
- Fruitful relationship with the manufacturer, and we have contributed to develop the design kit
- New Cadence Design Share Agreement model
- One test beam at CERN, one at DESY, and several at medical facilities
- 34 RD50-MPWx presentations in RD50 Workshops, plus many other presentations at conferences
- 12 peer-reviewed publications (+2 under review, + others in preparation)
- Countless meetings and emails
- Several PhD and undergraduate students: Ana Catalán, Jernej Debevc, Daniel Domenech, Fabian Förster, Klemens Flöckner, Matt Franks, Lukas Haider, William Holmkvist, Bernhard Pils, Sam Powell, Lingxin Meng, Thijs Niemeijer, Douwe Nobels, Patrick Sieberer, Christina Tsolanta, Chenfan Zhang
- Collaborative RD50 spirit... some groups have contributed with design, others with DAQ, others with measurements, others with skills and knowledge or access to specialised instrumentation, some groups with several things... everybody has always been welcome... together we have reached where we are today... **thanks everyone** 😊



Yes, we did it!

Back up slides

RD50-MPWx chip series – Overview

Parameter	RD50-MPW1	RD50-MPW2	RD50-MPW3	RD50-MPW4
Device size [mm x mm]	5 x 5 ⁽¹⁾	3.2 x 2.1	5.1 x 6.6	5.4 x 6.3
Pixel matrix size	40 x 78	8 x 8	64 x 64	64 x 64
Pixel size [μm x μm]	50 x 50	60 x 60	62 x 62	62 x 62
P-n spacing [μm]	3	8	8	8
In-pixel electronics	Analogue Digital	Analogue	Analogue Digital	Analogue Digital
Output data	Pixel address Time-stamp	Binary	Pixel address Time-stamp	Pixel address Time-stamp
Digital periphery	78 EOCs 2 LVDs lines	8 EOCs	32 EOCs, with 32-events 24-bit FIFOs 128-events 32-bit TX FIFOs I2C Wishbone bus 1 LVDs line	32 EOCs, with 16-events 24-bit FIFOs 64-events 32-bit TX FIFOs I2C Wishbone bus 1 LVDs line

⁽¹⁾Half of the chip has a pixel matrix for applications beyond physics

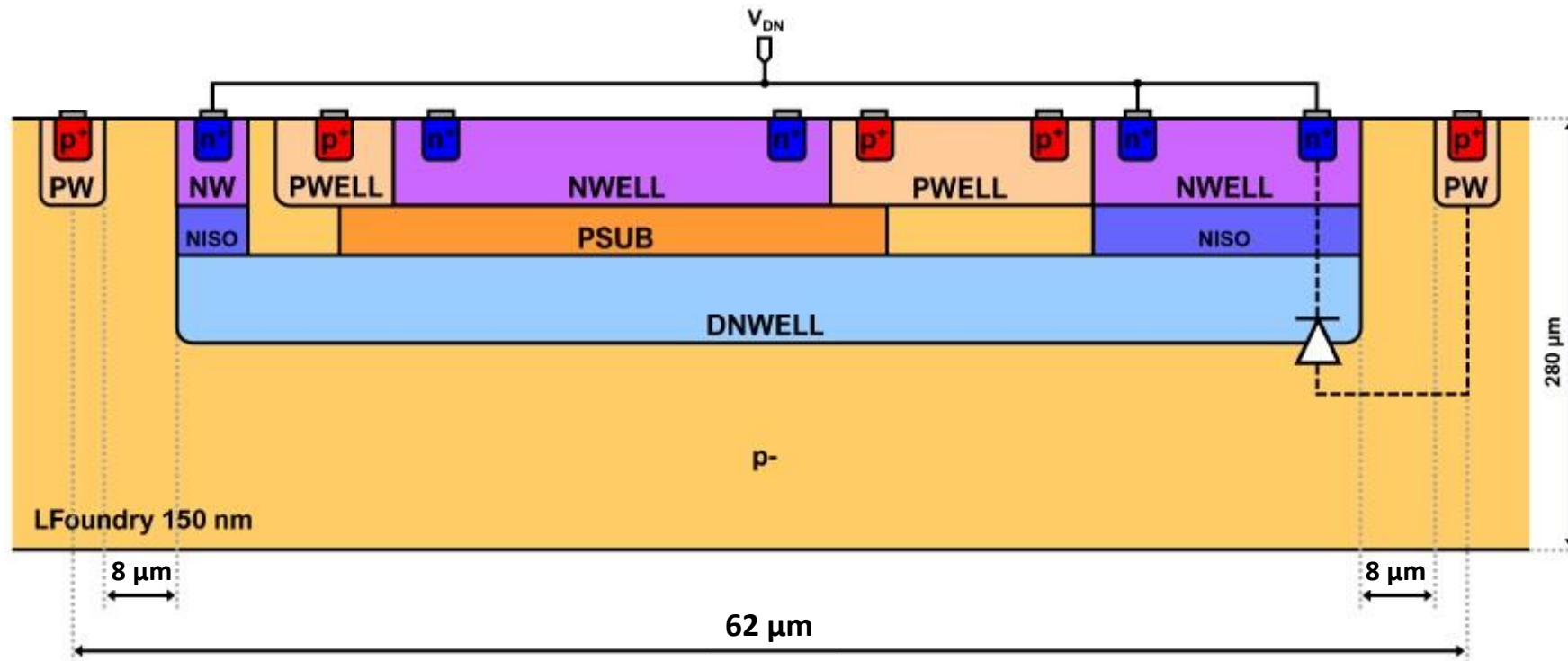
RD50-MPWx chip series – Overview

Parameter	RD50-MPW1	RD50-MPW2	RD50-MPW3	RD50-MPW4
Chip guard ring frame	None	1 n-ring 6 p-rings	1 n-ring 6 p-rings	1 n-ring 5 n-/p-rings
Substrate biasing	Through p-stop contacts	Through p-stop contacts	Through p-stop contacts	Through chip edge or backside
Substrate resistivity [kΩ·cm]	0.5 – 1.1 1.9	Standard 0.2 – 0.5 1.9 3	Standard 1.9 3	Standard 3
Device thickness [μm]	280	280	280	280
V _{BD} [V]	56	120	120	500 ⁽²⁾
I _{LEAK} [μA/pixel]	1	1E-4	1E-6	1E-6 ⁽²⁾
Depletion depth [μm]	118	110	Not tested	Fully depleted ⁽²⁾
ENC [mV]	50	2	< 140, > 50	50 ⁽²⁾
Efficiency [%]	Not tested	Not tested	> 98	> 99 ⁽²⁾

⁽²⁾Anticipated values for RD50-MPW4

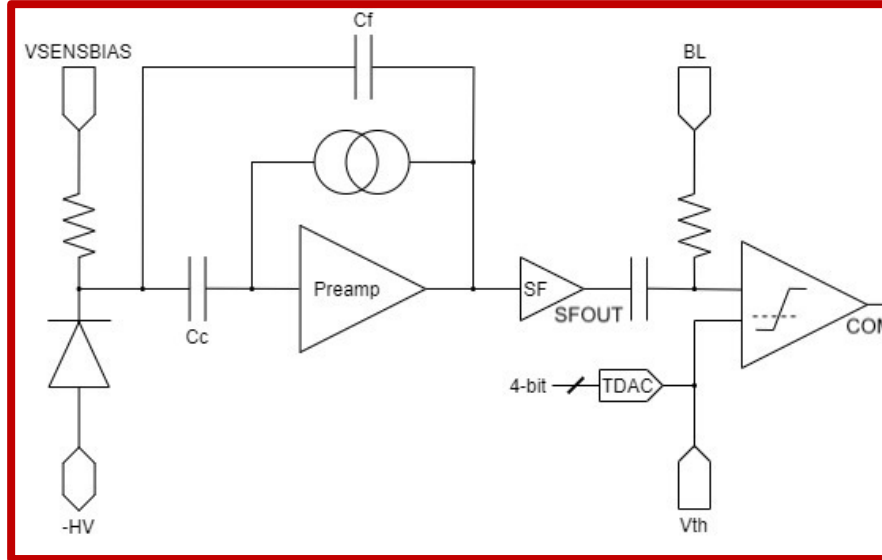
Process and sensor cross-section

- 150 nm HV-CMOS LFoundry
 - P-substrate/DNWELL sensing junction
 - Pixel readout electronics embedded inside DNWELL
 - CMOS electronics in sensing diode & isolated from DNWELL with PSUB

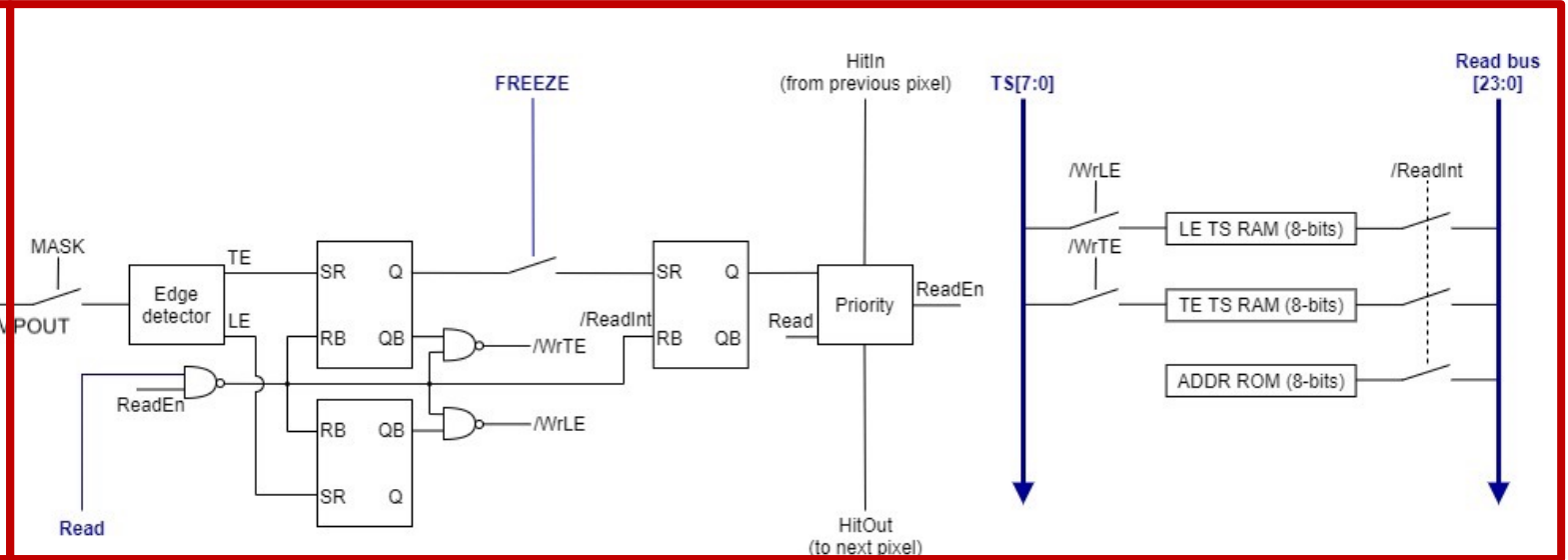


Pixel electronics

Analogue readout



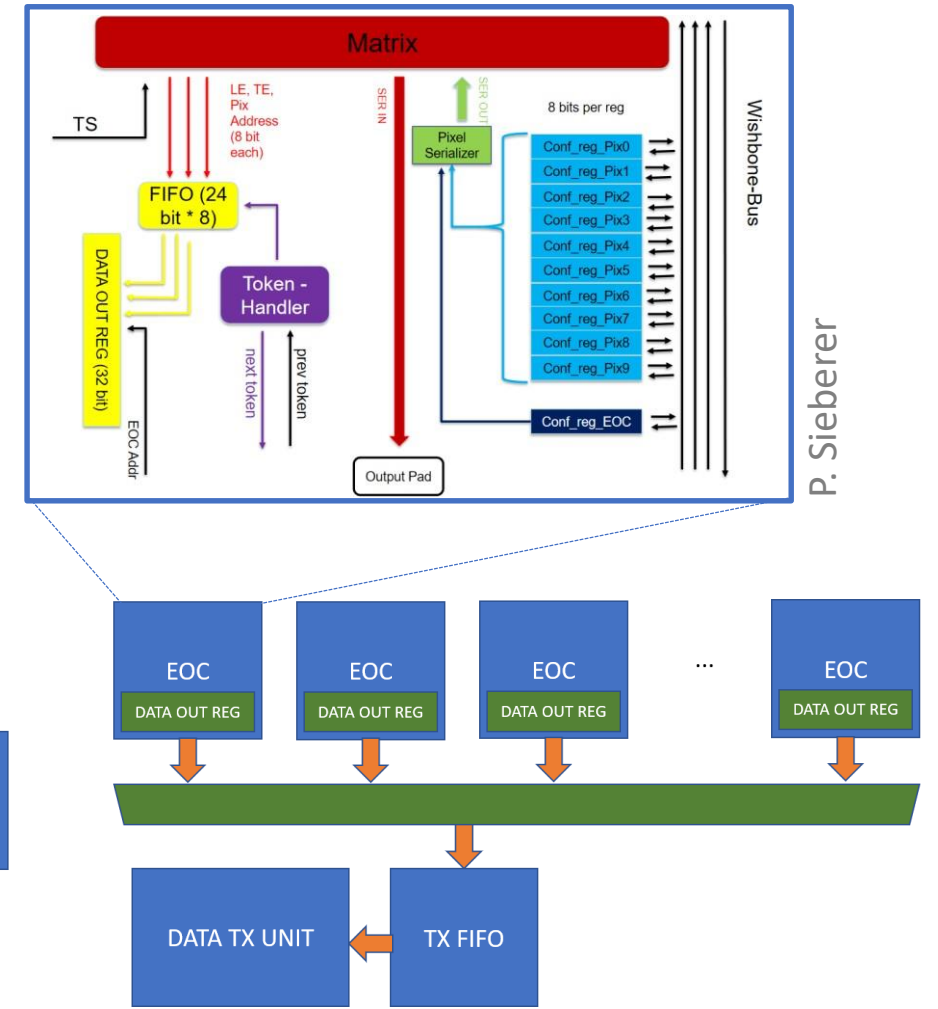
Digital readout



- **Column drain architecture (FE-I3 style)**
- **Electronics to**
 - Mask noisy pixels (MASK)
 - Possibility to pause digitisation of new hits until readout is complete (FREEZE)
 - 8-bit SRAM shift register for serial configuration
 - Pixel-trimming to compensate for threshold voltage variations (4-bits)
 - Flag to mask noisy pixels (1-bit)
 - Signals to enable/disable calibration circuit (1-bit), SFOUT (1-bit), COMPOUT (1-bit)

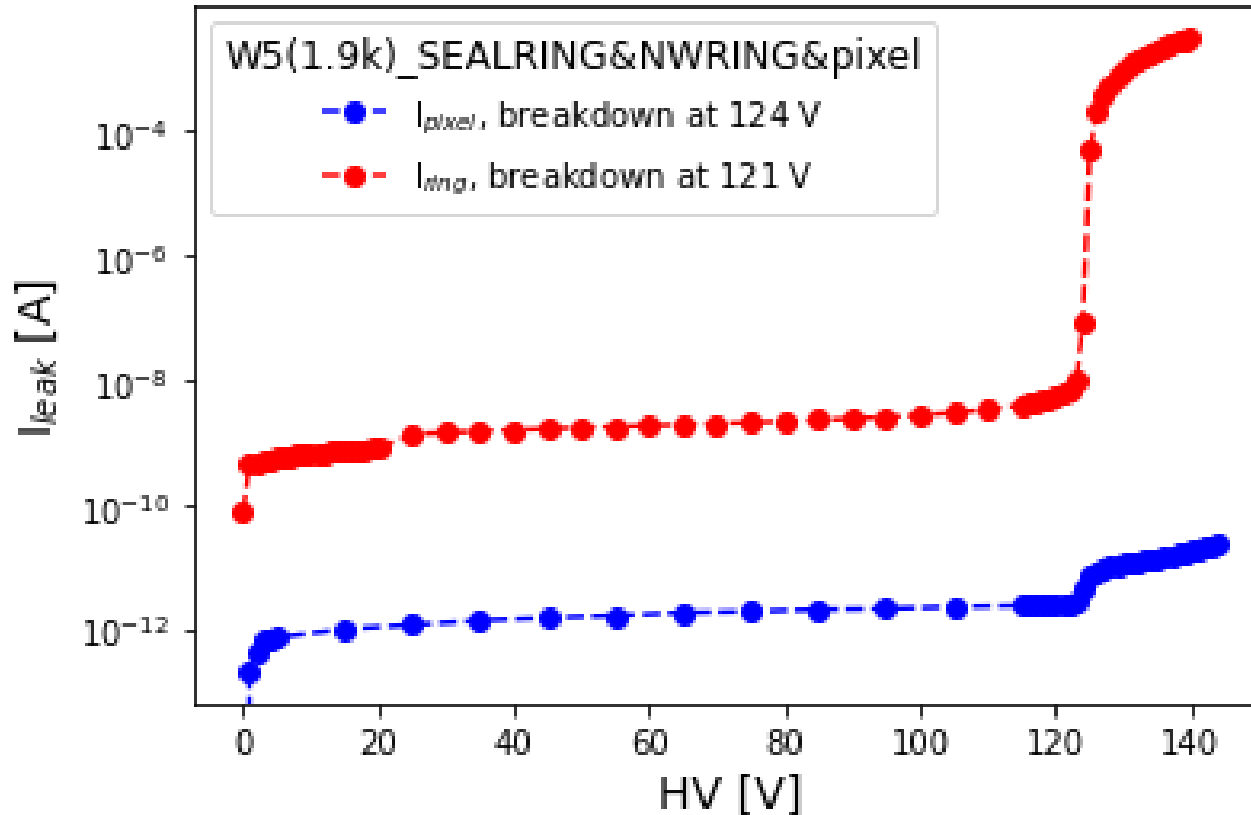
Digital periphery

- **End-Of-Column (EOC) architecture**
 - FIFO stores hit data (LE TS, TE TS and ADDR)
 - FSM reads double column
 - Token mechanism to determine which EOC is read out
- **Readout**
 - Pixel is read out immediately after hit (if FIFO is not full)
 - CU reads EOCs sequentially
 - Data stored temporarily in TX FIFO
 - Data TX unit with LVDS port @ 640 Mbps
- **Slow control**
 - Based on I2C protocol for external communication using internal Wishbone bus



RD50-MPW3 – I-V measurements

- Measurement using probe station with needles
- $V_{BD} > 120$ V ($V_{BD} > 300$ V in RD50-MPW4)
- I_{LEAK} per pixel in pA range before breakdown



RD50-MPW3 – Lab results

- High noise due to coupling effects (solved in RD50-MPW4)
- Pixel gain measured to be $82.9 \mu\text{V}/e^-$

